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June 9, 2000

BOX PATENT APPLICATION
Assistant Director For Patents
Washington, D.C. 20231

EXPRESS MAIL MAILING LABEL NO EL195372603US
DATE OF DEPOSIT: JUNE 9, 2000
I hereby certify that this paper or fee is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR § 1.10 on the dated indicated above and is addressed to BOX PATENT APPLICATION, Assistant Director for Patents, Washington, DC 20231

Derrick T. Gordon
Name of Person Mailing Paper or Fee

Derrick T. Gordon
Signature

June 9, 2000
Date of Signature

Re: New U.S. Patent Application
ACTUATOR AND DRIVING METHOD THEREOF
By: Shinya MATSUDA, Takashi MATSUO and Masayuki UYAMA
Attorney Docket: 15162/02100

Dear Sir:

Enclosed for filing are the following papers relating to ACTUATOR AND DRIVING METHOD THEREOF, Shinya MATSUDA, Takashi MATSUO and Masayuki UYAMA, inventors:

- (1) Specification;
- (2) Executed Declaration and Power of Attorney;
- (3) Formal Drawings (20 sheets);

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SINGAPORE
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Assistant Director For Patents
June 9, 2000
Page 2

- (4) Preliminary Amendment;
- (5) Certified Copies of the Priority Documents;
- (6) Transmittal of PrintEFS Patent Application Bibliographic Data;
- (7) Assignment of the invention to MINOLTA CO., LTD., with attached Recordation Form Cover Sheet;
- (8) Check in the amount of \$40.00 to cover the fee for recordal of Assignment; and
- (9) Check in the amount of \$846.00 to cover the filing fee of the application.

In the event the attached checks in the amount of \$40.00 and \$846.00 are not received with this correspondence, are not sufficient, or in the event additional fees are due, please charge the required fees during the pendency of this application (other than issue fee) to Sidley & Austin's Deposit Account No. 18-1260. Please credit any overpayment to Sidley & Austin's Deposit Account No. 18-1260.

All correspondence is to be directed to the Applicants' attorney at the Dallas address listed above.

Respectfully submitted,

By: James W. Williams
James W. Williams
Registration No. 20,047
Attorney for Applicants

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Enclosures

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re

U.S. application: Shinya MATSUDA, Takashi MATSUO and
Masayuki UEYAMA

For: ACTUATOR AND DRIVING METHOD THEREOF

U.S. Serial No.: To Be Assigned

Filed: Concurrently

Group Art Unit: To Be Assigned

Examiner: To Be Assigned

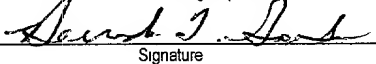
BOX PATENT APPLICATION

Assistant Director

for Patents

Washington, D.C. 20231

Dear Sir:

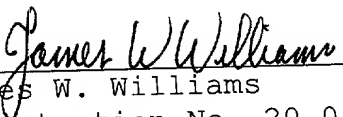
EXPRESS MAIL MAILING LABEL NO. EL195372603US DATE OF DEPOSIT JUNE 9, 2000 I hereby certify that this paper or fee is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 C F R § 1.10 on the dated indicated above and is addressed to BOX PATENT APPLICATION, Assistant Director for Patents, Washington, DC 20231. Derrick T. Gordon Name of Person Mailing Paper or Fee  Signature June 9, 2000 Date of Signature

TRANSMITTAL OF PrintEFS PATENT APPLICATION

BIBLIOGRAPHIC DATA

Submitted herewith is bibliographic data (2 pages) for
the above-identified application, in the PrintEFS Version
1.0.1 program format.

Respectfully submitted,


James W. Williams
Registration No. 20,047
Attorney for Applicants

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June 9, 2000

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APPLICATION INFORMATION

Title Line One:: ACTUATOR AND DRIVING METHOD THEREOF
Total Drawing Sheets:: 20
Formal Drawings?: Yes
Application Type:: Utility
Docket Number:: 15162/02100
Secrecy Order in Parent Appl.?: No

REPRESENTATIVE INFORMATION

Registration Number One:: 39095
Registration Number Two:: 27189
Registration Number Three:: 37803
Registration Number Four:: 38425
Registration Number Five:: 29160
Registration Number Six:: 30067
Registration Number Seven:: 44196
Registration Number Eight:: 44234
Registration Number Nine:: 38595
Registration Number Ten:: 41341
Registration Number Eleven:: 20047

PRIOR FOREIGN APPLICATIONS

Foreign Application One:: 11-166919
Filing Date:: 06-14-1999
Country:: JAPAN
Priority Claimed:: Yes
Foreign Application Two:: 11-185197
Filing Date:: 06-30-1999
Priority Claimed:: Yes

Source:: PrintEFS Version 1.0.1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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U.S. application: Shinya MATSUDA, Takashi MATSUO and
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Derrick T. Gordon

Name of Person Mailing Paper or Fee

Derrick T. Gordon
Signature

June 9, 2000

Date of Signature

PRELIMINARY AMENDMENT

Please amend the above identified U.S. patent
application as follows:

In the Specification:

Page 1, line 4, delete "references" and insert --
reference--.

Page 2, line 3, after "at", insert --a--.

Page 2, line 13, delete "Still furthermore", and
insert --Also--.

Page 3, line 13, after "Since", insert --the--.

Page 3, line 19, delete "Still furthermore", and
insert --Also--.

Page 3, line 22, delete "SUMMERY", and insert
--SUMMARY--.

Page 3, line 24, delete "and easily", and insert --and
which can easily--.

Page 5, line 13, delete "DIGs.", and insert --FIGs.--.

Page 6, line 2, delete "condition in which", and
insert --condition.--.

Page 7, line 23, delete "whole the", and insert --the
whole--.

Page 10, line 21, delete "first".

Page 15, line 3, delete "has been".

Page 17, line 2, delete "was", and insert --were--.

Page 23, line 15, delete "side", and insert --sides--.

Page 23, line 23, delete "side", and insert --sides--.

Page 24, line 3, delete "than that", and insert --that
than--.

Page 28, line 11, after "in", insert --the--.

Page 29, line 21, delete "second first", and insert
--second--.

Page 36, line 23, delete "second first", and insert
--second--.

Page 38, line 12, delete "Still furthermore", and
insert --Also--.

Page 40, line 12, delete "first".

Page 41, line 19, delete "ceramics which is a", and
insert --ceramic--.

Page 41, line 20, after "has", insert --a--.

Page 41, line 22, delete "ceramics", and insert
--ceramic material--.

Page 50, Abstract, line 7, delete "increases", and
insert --increased--.

In The Claims:

Page 46, claim 7, line 6, delete "firs", and insert
--first--.

Page 46, claim 8, line 2, delete "gas", and insert
--has--.

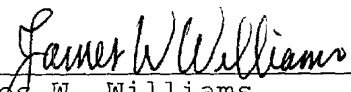
Page 48, claim 14, line 7, delete "firs", and insert
--first--.

REMARKS

By this Preliminary Amendment, the specification and
claims 7, 8, and 14, have been amended to correct

typographical errors. This Amendment does not increase the total number of claims, does not increase the number of independent claims, and does not present any multiple dependency claims. However, if a fee is required, please charge any fee (other than an issue fee) required during the pendency of this U.S. patent application to Sidley & Austin's Deposit Account 18-1260.

Respectfully submitted,


James W. Williams
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June 9, 2000

ACTUATOR AND DRIVING METHOD THEREOF

This application is based on patent applications Hei.11-166919 and Hei.11-185197 filed in Japan, the contents of which are hereby incorporated by references.

BACKGROUND OF THE INVENTION

1. Field of the Invention

This invention relates to an actuator, such as a truss type actuator for generating an elliptic movement of a driven object by composition of displacements of a plurality of displacing devices where the displacing devices are driven by using resonance phenomenon, and methods for driving the actuator.

2. Description of the Related Art

A first conventional truss type actuator is shown in "Development of a Small Actuator with Three Degrees of Rotational Freedom (1st Report)" by K. SASAE et. al., Journal of Precision Engineering Institution, Vol.61, No.31, 1995. In the first conventional actuator, a chip member is provided at a crossing point of three lamination type piezoelectric devices. The piezoelectric devices are driven for moving the chip member so as to trail a spherical surface, so that a spherical driven member can be revolved in an optional direction. Since the piezoelectric devices are driven in non-resonance mode, the displacement of the piezoelectric devices are not so large and the driving efficiency of the actuator is relatively low.

A second conventional truss type actuator is shown in "Manufacture and Estimation of Thin Ultrasonic Linear Motor" by S.

NAGATOME, et. al., Collection of Lecture of Precision Engineering Institution, in Spring, 1998. In the second conventional actuator, a steel plate is blanked so that two displacing portions cross at right angle. Piezoelectric devices are fixed on respective displacing portions. One of the piezoelectric device is resonantly driven for colliding the peak at the crossing point of the displacing portions with a driven member obliquely. Thus, the driven member is moved in a predetermined direction. Since the piezoelectric device is driven in resonance mode, the displacement of the piezoelectric device can be made larger. The peak of the steel plate, however, collides with the driven member linearly, so that acoustic noise and vibrations of the actuator are relatively larger. Furthermore, the steel plate and the driven member are heavily worn. Still furthermore, the actuator has no mechanism for detecting the displacement of the piezoelectric device, so that it is difficult to control the moving speed of the driven member.

A third conventional traveling wave type actuator is shown in the publication of "Admission into Ultrasonic Motor" by Sogo Denshi Shuppansha Japan. In the third conventional actuator, a plurality of piezoelectric devices are adhered on a circular elastic member at a predetermined interval. When the elastic member is resonantly vibrated by driving the piezoelectric devices, traveling waves are formed in a direction parallel to an axis of the circular elastic member. A driven member disposed on the circular elastic member can be rotated around the axis of the circular elastic member. Since the

elastic member and the driven member are shaped to be circular, freedom for designing an apparatus using the actuator becomes narrower.

A fourth conventional linear actuator is shown in "First Report of Piezoelectric Traveling Wave type Linear Actuator" by H. OKU, et. al., Collection of Lecture of Precision Engineering Institution, in Spring, 1995. In the fourth conventional actuator, a plurality of piezoelectric devices are adhered on a side wall of an endless elastic member. Each piezoelectric device is driven by two kinds of the natural vibration modes, and the displacements of the vibrations of the piezoelectric devices are compounded so as to generate the traveling waves on the surface of the elastic member and parallel to the endless section of the elastic member. Since whole of the elastic member is vibrated, a mass of an object to be vibrated by the piezoelectric devices becomes larger. Thus, the frequencies of the driving signals for driving the piezoelectric device become smaller, and an output of the actuator become smaller. Furthermore, it is difficult not only to control the condition for resonantly vibrating the elastic member but also to connect the elastic member. Still furthermore, since the deformation of the elastic member is complex, it is difficult to control the condition to obtain a desired elliptic movement.

SUMMARY OF THE INVENTION

An object of this invention is to provide an actuator having a simple configuration and high driving efficiency, and easily be controlled.

An actuator in accordance with an aspect of this invention comprises a plurality of displacing devices for generating displacements; a compound member connected to the displacing devices and for compounding displacements of the displacing devices; a base member for folding base ends of the displacing devices at which the compound member is not connected; a pressing member for pressing the compound member to an object to be driven; and a driver for resonantly driving the displacing devices so as to move the compound member an elliptic or a circular trail.

By the above-mentioned configuration, the displacing devices are resonantly driven, so that the displacements of the displacing devices are enlarged. Thus, the driving efficiency of the actuator can be increased.

BRIEF DESCRIPTION OF THE DRAWINGS

FIG.1 is a front view showing a configuration of a lamination type piezoelectric device used as a displacing device in an embodiment of this invention;

FIG.2 is a graph for showing a relation between displacement of a piezoelectric device and electric field applied to the piezoelectric device;

FIG.3 is front view for showing a configuration of an actuator in this embodiment;

FIG.4 is a block diagram for showing a configuration of a driving circuit of the actuator in this embodiment;

FIG.5 is a schematic view for showing the actuator pressed on

a rotor in this embodiment;

FIG.6 is a graph for showing waveforms of driving signals applied to the piezoelectric devices of the actuator;

FIGs.7A to 7E are schematic views for showing rotation mechanism of the rotor by the actuator in this embodiment;

FIGs.8A to 8E are graphs for showing trails of a chip member when amplitude of vibrations of two piezoelectric devices are equal to each other but the phase difference of the vibrations are respectively 0, 45, 90, 135 and 180 degrees;

FIGs.9A to 9D are schematic views for showing deformation of the actuator in the same phase mode and the opposite phase mode under a constraint condition;

DIGs.10A to 10D are schematic views for showing deformation of the actuator in the same phase mode and the opposite phase mode under a non-constraint condition;

FIG.11 is a schematic view for showing a model of the expansive vibration in the opposite phase mode under the constraint condition;

FIG.12 is a schematic view for showing a model of the expansive vibration in the same phase mode under the constraint condition;

FIGs.13A and 13B are schematic views for showing a model of the expansive vibration in the opposite phase mode under the non-constraint condition;

FIGs.14A and 14B are schematic views for showing a model of

the expansive vibration in the opposite phase mode under the non-constraint condition in which

FIGs.15A to 15C are schematic views for showing a model of the expansive vibration in the same phase mode under the non-constraint condition;

FIG.16 is a schematic view for showing an equivalent circuit of the piezoelectric device;

FIG.17 is a block diagram for showing a configuration of a modified driving circuit of the actuator in this embodiment;

FIGs.18A to 18C are graphs for showing resonance characteristics of the piezoelectric device;

FIGs.19A to 19C are graphs for showing an example of resonance characteristics of two different piezoelectric devices;

FIGs.20A to 20C are schematic views for showing examples of trails of the chip member due to error components of the piezoelectric devices;

FIGs.21A to 21C are graphs for showing waveforms of driving signals and currents flowing in the piezoelectric devices;

FIG.22 is a block diagram for showing a configuration of another modified driving circuit of the actuator in this embodiment;

FIG.23 is a block diagram for showing a configuration of still another modified driving circuit of the actuator in this embodiment;

FIG.24 is front view for showing a modified configuration of an actuator in this embodiment.

DETAILED DESCRIPTION OF THE EMBODIMENT

An embodiment of this invention is described. A configuration of a lamination type piezoelectric device used as a displacing device in this embodiment is shown in FIG.1. The lamination type piezoelectric device 10 is formed by piling up of a plurality of ceramic thin plates 11 and electrodes 12 and 13 alternately disposed. The ceramic thin plates 11 is made of such as PZT showing piezoelectric characteristic. The ceramic thin plates 11 and the electrodes 12 and 13 are fixed by an adhesive. Two groups of electrodes 12 and 13 which are alternately disposed are respectively connected to a driving power source 16 via cables 14 and 15. When a predetermined voltage is applied between the cables 14 and 15, an electric field is generated in each ceramic thin plate 11 disposed between the electrodes 12 and 13. The direction of the electric field in the ceramic thin plates alternately disposed is the same. Thus, the ceramic thin plates 11 are piled in a manner so that polarization direction of the ceramic thin plates 11 alternately disposed becomes the same. In other words, the polarization directions of adjoining two ceramic thin plates are opposite to each other. Furthermore, protection layers 17 are provided on both ends of the piezoelectric device 10.

When a DC driving voltage is applied between the electrodes 12 and 13, each ceramic thin plate 11 expands or contracts in the same direction. Thus, whole the piezoelectric device 10 can expand and contract. When the electric field in the ceramic thin plate 11 is sufficiently small and hysteresis of the displacement of the ceramic

thin plate 11 can be ignored, it is possible to consider that a relation between the displacement of the piezoelectric device 10 and the electric field generated between the electrodes 12 and 13 is linear. The relation between the displacement of the piezoelectric device and the electric field is shown in FIG.2. In FIG.2, the abscissa shows the intensity of electric field and the ordinate shows the ratio of strain of the piezoelectric device.

When an AC driving voltage (signal) is applied between the electrodes 12 and 13 by the driving power source 16, all the ceramic thin plates 11 repeat the expansion and the contraction in the same direction corresponding to the intensity of the electric fields. As a result, the piezoelectric device 10 can repeat the expansion and the contraction. The piezoelectric device 10 has an inherent resonance frequency defined by the configuration and the electric characteristics thereof. When the frequency of the AC driving voltage coincides with the resonance frequency of the piezoelectric device 10, the impedance of the piezoelectric device 10 is reduced and the displacement thereof increases. Since the displacement of the piezoelectric device 10 is small with respect to the size thereof, it is preferable to utilize the resonance phenomenon for driving the piezoelectric device by a low driving voltage.

A configuration of a truss type actuator in this embodiment is shown in FIG.3. A first piezoelectric device 10 and a second piezoelectric device 10' serving as displacing devices are disposed to cross substantially at right angle. A chip member 20 serving as a

compound member for compounding the displacements of the first piezoelectric device 10 and the second piezoelectric device 10' is disposed at crossing point and connected on respective top ends of the first piezoelectric device 10 and the second piezoelectric device 10' by an adhesive. Base ends of the first piezoelectric device 10 and the second piezoelectric device 10' are respectively fixed on a base member 30 by an adhesive. As a material of the chip member 20, it is preferable to use a material such as tungsten having high friction factor and high wear resistance. As a material of the base member 30, it is preferable to use a material such as stainless steel having high workability and strength. As a material of the adhesive, it is preferable to use a material such as epoxy resin having high adhesive strength. The first piezoelectric device 10 and the second piezoelectric device 10' are substantially the same as the piezoelectric device 10 shown in FIG.1. Elements for constituting the second piezoelectric device 10' are distinguished from those of the first piezoelectric device 10 by adding (') to the numerals.

In this actuator, the first piezoelectric device 10 and the second piezoelectric device 10' are respectively driven by AC driving signals having a predetermined phase difference, so that the chip member 20 can be moved elliptically or circularly. When the chip member 20 is pushed on, for example, a cylindrical surface of a rotor 40 which can rotate around a predetermined axis, the elliptic or circular movement of the chip member 20 can be converted to the rotation of the rotor 40. Alternatively, when the chip member 20 is pushed on a plane surface

of a rod shaped member (not shown), the elliptic or circular movement of the chip member 20 can be converted to a rectilinear motion of the rod shaped member. As a material of the rotor 40, it is preferable to use a material such as aluminum having a light weight. Furthermore, it is preferable to form an anodic oxide coating on the surface of the rotor 40 for preventing the wear due to the friction between the chip member 20 and the rotor 40.

A block diagram of a driving circuit is shown in FIG.4. An oscillator 50 generates sine wave signals having a predetermined frequency coinciding with resonance frequencies of the first piezoelectric device 10 and the second piezoelectric device 10' in the same phase mode and in the opposite phase mode which will be described below. A phase controller 51 controls a delay circuit 52 corresponding to rotation speed, driving torque, rotation direction of the rotor 40 so as to generate sine wave signals having a predetermined phase difference. An amplitude controller 53 controls a first amplifier 54 and a second amplifier 55 for amplifying two sine wave signals having a phase difference. The amplified sine wave signals amplified by the first amplifier 54 and the second amplifier 55 are respectively applied to the first piezoelectric device 10 and the second first piezoelectric device 10'.

A principle of the rotation of the rotor 40 by the actuator is described. FIG.5 shows that the actuator shown in FIG.3 is pressed on the rotor 40 by a pressure F of a spring 41. In FIG.5, the symbol μ designates the friction factor. Furthermore, the voltage of the

driving signals applied to or the displacements of the first piezoelectric device 10 and the second piezoelectric device 10' are shown in FIG.6.

When the driving signals having the phase difference shown in FIG.6 are respectively applied to the first piezoelectric device 10 and the second piezoelectric device 10', the first piezoelectric device 10 and the second piezoelectric device 10' are displaced as sine wave form. As a result, the chip member 20 connected to the first piezoelectric device 10 and the second piezoelectric device 10' moves elliptically or circularly.

When the frequency of the driving signals applied to the first piezoelectric device 10 and the second piezoelectric device 10' is small and the rotation speed of the chip member 20 is slow, the actuator follows the displacement of the chip member 20 by the pressure F of the spring 41. Thus, the chip member 20 cannot be departed from the surface of the rotor 40, so that the chip member 20 is reciprocally driven with contacting the rotor 40. Thus, the rotor 40 cannot be rotated.

On the other hand, when the frequency of the driving signals applied to the first piezoelectric device 10 and the second piezoelectric device 10' is larger and the rotation speed of the chip member 20 is fast, the actuator cannot follow the displacement of the chip member 20, so that the chip member 20 can temporarily be departed from the surface of the rotor 40. Thus, the chip member 20 can be moved in a predetermined direction while the chip member 20

is departed from the surface of the rotor 40, and the chip member 20 can be moved in the opposite direction with the rotor 40 while the chip member 20 contacts the rotor 40. As a result, the rotor 40 can be rotated.

The rotation mechanism of the rotor 40 by the actuator is shown in FIGs.7A to 7E. FIGs.7A and 7E show that both of the first piezoelectric device 10 and the second piezoelectric device 10' expand and the chip member 20 contacts the surface of the rotor 40. FIG.7B shows that the first piezoelectric device 10 contracts, the second piezoelectric device 10' expands and the chip member 20 is departed from the surface of the rotor 40. FIG.7C shows that both of the first piezoelectric device 10 and the second piezoelectric device 10' contract and the chip member 20 is departed from the surface of the rotor 40. FIG.7D shows that the first piezoelectric device 10 expands, the second piezoelectric device 10' contracts, but the actuator follows the movement of the chip member 20 so that the chip member 20 contacts the surface of the rotor 40. As can be seen from FIGs.7A to 7E, it is possible to rotate the rotor 40 by departing the chip member 20 from the surface of the rotor 40.

Subsequently, the driving signals for driving the first piezoelectric device 10 and the second piezoelectric device 10' are described. When two independent movements crossing at right angle are compounded, the crossing point moves along an elliptic trail including the circular trail defined by the Lissajous' equation. FIGs.8A to 8E show trails of the chip member 20 when the amplitude

of the vibrations of the first piezoelectric device 10 and the second piezoelectric device 10' are equal to each other but the phase difference of the vibrations are respectively 0, 45, 90, 135 and 180 degrees.

As mentioned above, it is possible to control the rotation direction, the rotation speed and the torque of the rotor 40 by controlling the trail of the chip member 20. More concretely, when the diameter of the trail of the chip member 20 in the tangential direction of the rotor 40 is enlarged, the rotation speed of the rotor 40 can be increased. Alternatively, when the diameter of the trail of the chip member 20 in the normal direction of the rotor 40 is enlarged, the torque of the rotor 40 can be increased. When the phase difference between the driving signals for the first piezoelectric device 10 and the second piezoelectric device 10' are reversed, the rotation direction of the rotor 40 can be reversed.

Subsequently, a method for controlling the trail of the chip member 20 to be circular is considered. The first piezoelectric device 10 and the second piezoelectric device 10' are respectively driven under resonance vibration by using the driving signals with the phase difference of 90 degrees.

The actuator shown in FIG.3 was actually manufactured. When the first piezoelectric device 10 and the second piezoelectric device 10' were respectively driven by the driving signals having the frequencies near to the resonance frequency of the first piezoelectric devices 10 and the second piezoelectric device 10', the trail of the chip

member 20, which was essentially to be circular, was deformed to be elliptical largely in which the axes of the ellipse are largely slanted from the axes corresponding to the tangent and the normal at the contacting point of the rotor 40 and the chip member 20. In the experimental process, it was found that the vibrations of the first piezoelectric device 10 and the second piezoelectric device 10' are affected each other via the chip member 20 and the base member 30, so that the above-mentioned phenomenon occurred. Since the vibration of one piezoelectric device is transmitted to the other piezoelectric device with the phase delay of about 90 degrees, the vibration transmitted thereto is superimposed on the displacement of the piezoelectric device owing to the driving signals. Thus, the displacement of the piezoelectric device displacing second is enlarged, and the displacement of the other piezoelectric device displacing first is contracted. As a result, the trail of the chip member 20 was deformed to be elliptical expanded in the direction parallel to the displacement of the piezoelectric device displacing second.

For solving this phenomenon, it is necessary to prevent the transmission of the vibration of one piezoelectric device to the other as small as possible, and to realize a system in which two piezoelectric devices can be vibrated independently. When the system is realized, the trail of the chip member 20 can be made circular in every frequency band including the resonance frequency. Furthermore, when the amplitude and the phase difference of the driving signals are varied, the shape of the trail of the chip member 20

can optionally be varied, if necessary. Thus, the rotation speed of the rotor 40 which is the driven member can be controlled.

The inventors have been supposed that the system can be realized by a condition that the resonance frequency of actuator of the expansive vibration in the same phase mode coincides with that of the expansive vibration in the reverse phase mode. The same phase mode is defined that the phases of displacements of two piezoelectric devices coincide with each other. The opposite phase mode is defined that the phases of the displacements of two piezoelectric devices are opposite to each other. The analyzed results by finite element method will be described below.

FIGs.9A to 9D respectively show the deformation of the actuator in the same phase mode and the opposite phase mode under a constraint condition. The constraint condition is defined that the rigidity of the base member 30 is higher and the base member 30 is hardly deformed by the displacements of the first piezoelectric device 10 and the second piezoelectric device 10'.

FIG.9A shows the actuator in the resonance mode in which the expansive vibration occurs in the same phase mode. The frequency of the vibration is, for example, about 51 kHz. FIG.9B shows the actuator in the resonance mode in which the expansive vibration occurs in the opposite phase mode. The frequency of the vibration is, for example, about 51 kHz. FIG.9C shows the actuator in the resonance mode in which the bending vibration occurs in the same phase mode. The frequency of the vibration is, for example, about

157 kHz. FIG.9D shows the actuator in the resonance mode in which the bending vibration occurs in the opposite phase mode. The frequency of the vibration is, for example, about 74 kHz. The frequency in each mode is defined by characteristics such as a material and a mass of each portion of the actuator.

FIGs.10A to 10D respectively show the deformation of the actuator in the same phase mode and the opposite phase mode under a non-constraint condition. The non-constraint condition is defined that the rigidity of the base member 30 is lower and the base member 30 can be deformed by the displacements of the first piezoelectric device 10 and the second piezoelectric device 10'.

FIG.10A shows the actuator in the resonance mode in which the expansive vibration occurs in the same phase mode. The frequency of the vibration is, for example, about 46 kHz. FIG.10B shows the actuator in the resonance mode in which the expansive vibration occurs in the opposite phase mode. The frequency of the vibration is, for example, about 62 kHz. FIG.10C shows the actuator in the resonance mode in which the bending vibration occurs in the same phase mode. The frequency of the vibration is, for example, about 79 kHz. FIG.10D shows the actuator in the resonance mode in which the bending vibration occurs in the opposite phase mode. The frequency of the vibration is, for example, about 72 kHz.

In this embodiment, the actuator moves the chip member 20 by using the expansive vibrations of the first piezoelectric device 10 and the second piezoelectric device 10'. The deformations shown in

FIGs.9A, 9B, 10A and 10B are noticed. When the characteristics of the actuator was adjusted so as to coincide the frequency of the actuator in the same phase mode with that in the opposite phase mode, the trail of the chip member became substantially a circle. The above-mentioned supposition was supported.

Subsequently, conditions of the actuator for coinciding the frequencies in the same phase mode and in the opposite phase mode with each other will be described.

1. Modeling of the expansive vibration in the opposite phase mode under the constraint condition is described. The expansive vibration in the opposite phase mode can be regarded as an expansive vibration system configured by a spring with a mass and a weight as shown in FIG.11. It, however, is difficult to obtain a natural frequency of the spring with a mass analytically, so that the Rayleigh method, which is generally used for supposing the deformation curve of a spring or a beam, is used approximately for obtaining the solution.

The mass of the spring in a unit length is designated by a symbol " μ ", a spring constant is designated by a symbol " k ", a length of the spring is designated by a symbol " L ". When an end of the spring is supported, the natural frequency of the expansive vibration is obtained as follows.

When it is assumed that a free end of the spring is vibrated as a simple harmonic motion in which the displacement of the free end is shown by $x(t) = X \cos \omega t$ and a displacement at a position distant a

distance "y" from the free end $x_y(t)$ is in proportion to "y/L", the displacement $x_y(t)$ is shown by $x_y(t)=(y/L)\cos \omega t$. Thus, the kinetic energy E_k of the spring is shown by the following equations.

$$\begin{aligned} E_k &= (1/2) \int \mu (dx_y/dt)^2 dy \\ &= (1/2) \mu \omega^2 X^2 \sin^2 \omega t \int (y/L)^2 dy \\ &= (1/6) \mu L \omega^2 X^2 \sin^2 \omega t \end{aligned}$$

On the other hand, the potential energy E_p of the spring is shown by the following equation.

$$E_p = (1/2) K x(t)^2 = (1/2) K X^2 \cos^2 \omega t$$

Since the largest value of the kinetic energy E_k of the spring is equal to that of the potential energy E_p of the spring by the energy method, the following equation is composed.

$$(1/6) \mu L \omega^2 X^2 = (1/2) K X^2$$

Thus, the natural frequency " ω " of the spring with the mass "m" is shown as follows.

$$\omega^2 = K / (\mu L / 3) = K / (m / 3)$$

On the contrary, the natural frequency of a spring with no mass and having the same spring constant is shown as $\omega^2 = K / M$, when an end of the spring is supported and a weight having a mass M is connected on the other end.

In other words, the natural frequency of the spring with a mass is equivalent to that of a system configured by a spring with no mass having the same spring constant and a weight having a mass of 1/3 of the tare weight of the spring with a mass and connected on an end of the spring with no mass.

Subsequently, when a mass of the chip member is designated by a symbol "M", a mass of the piezoelectric device is designated by a symbol "m" ($m_1=m/3$), a displacement at an end of the piezoelectric device is designated by a symbol "x", and a spring constant is designated by a symbol " k_1 ", the potential energy E_p and the kinetic energy E_k of the system are shown by the following equations.

$$E_p = (1/2)k_1x^2 \times 2$$

$$E_k = (1/2)M(\sqrt{2}dx/dt)^2 + (1/2)m_1(dx/dt)^2 \times 2$$

When $X(t) = X \cos \omega t$, and the energy method is used, it becomes $k_1X^2 = M\omega^2X^2 + m_1\omega^2X^2$.

Hereupon, when a tension, a stress, an elastic modulus and a strain of the piezoelectric device are respectively designated by symbols "T", " σ ", "E" and " ε ", the Hooke's law becomes as follows.

$$T = k_1X, \quad \sigma = E\varepsilon$$

When a length and an area of a cross-section of the piezoelectric devices are designated by symbols "L" and "S", it becomes $\sigma = T/S$, and $\varepsilon = x/L$, so that $k_1 = SE/L$. Thus, the frequency " ω_1 " of the expansion vibration in the opposite phase mode is shown by the following equation (1).

$$\omega_1^2 = k_1/(M+m_1) = SE/L(M+m/3) \quad \cdots (1)$$

2. Modeling of the expansive vibration in the same phase mode under the constraint condition is described. The expansive vibration in the same phase mode can be regarded as a compounded system of an expansive vibration system configured by a spring with a

mass and a weight and of a bending vibration system configured by a half of a beam both ends of which are supported, as shown in FIG.12. The natural frequency of the compounded vibration system configured by a plurality of restoring elements and inertia elements can be supposed by compounding frequencies of respective independent systems (It corresponds to a method for compounding vibration frequencies). Since the restoring elements are connected in parallel with each other and the inertia elements are connected in series, the natural frequency of the compounded system can be obtained by addition of the spring constants and the masses of the independent systems.

Since the expansive vibration in the same phase mode is the same as that in the opposite phase mode, so that the natural frequency " ω_2 " of the compounded system is shown by the following equation, when the spring constant in the bending vibration is designated by a symbol " k_2 " and an equivalent mass thereof is designated by a symbol " m_2 ".

$$\omega_2^2 = (k_1 + k_2) / (M + m_1 + m_2)$$

When a density, an area of a cross-section, a bending rigidity and a length of a beam with a mass are respectively designated by symbols " ρ ", " S ", " EI " and " L ", and when both ends of the beam are supported, a natural frequency of the bending vibration of the beam can be obtained as follows.

The potential energy E_p and the kinetic energy E_k of the beam in the bending vibration are shown by the following equations.

$$E_p = (1/2) \int EI (d^2y/dx^2)^2 dx$$

$$E_k = (1/2) \int \rho S (dy/dt)^2 dx$$

When a static strain curve of the beam is designated by $Y(x)$, and the vibration is assumed to be shown by $y(x,t) = Y(x)\cos \omega t$, the above-mentioned equations are modified to be the following equations.

$$E_p = (1/2) EI \cos^2 \omega t \int (d^2Y(x)/dx^2)^2 dx$$

$$E_k = (1/2) \rho S \omega^2 \cos^2 \omega t \int Y(x)^2 dx$$

Furthermore, when both ends of the beam are supported and the beam receives a load evenly distributed, the strain curve $Y(x)$ is shown by the following equation.

$$Y(x) = (\rho S / 24EI) x^2 (L-x)^2$$

This $Y(x)$ is substituted into the above-mentioned equations of the potential energy E_p and the kinetic energy E_k .

$$\begin{aligned} E_p &= (1/2) EI \cos^2 \omega t (\rho S / 24EI)^2 \int (12x^2 - 12Lx + 2L^2) dx \\ &= (1/2) EI \cos^2 \omega t (\rho S / 24EI)^2 \times (4/5) L^5 \end{aligned}$$

$$\begin{aligned} E_k &= (1/2) \rho S \omega^2 \cos^2 \omega t (\rho S / 24EI)^2 \int x^4 (L-x)^4 dx \\ &= (1/2) \rho S \omega^2 \cos^2 \omega t (\rho S / 24EI)^2 (1/630) L^9 \end{aligned}$$

Thus, the natural frequency of the beam both ends of which are supported and having a mass "m" is shown by the following equation.

$$\omega^2 = 4 \times 630 EI / 5 \rho S L^4 = 504 EI / mL^3$$

On the other hand, when a weight with a mass M is connected at the center of the beam both ends of which are supported, the displacement "y" can be shown as $y = MgL^3 / 192EI$. The natural frequency " ω " of the beam is shown by the following equation.

$$\omega^2 = K/L = 192EI/ML^3$$

Thus, the natural frequency of the beam with a mass is equivalent to that of a system configured by a beam with no mass and having the same bending rigidity and a weight connected at the center of the beam with no mass and having a weight of $192/504 \doteq 1/2.63$ of the tare weight of the beam with a mass. When $L'=L/2$ and $M'=M/2$, since the displacements "y" are equal, it becomes

$$y = MgL^3/192EI = (2M')g(2L')^3/192EI = M'gL'^3/12EI.$$

Thus, a spring constant " K_2 " and an equivalent mass " m_2 " of a vibration system by the half of the beam both ends of which are supported are shown by the following equations.

$$K_2 = 12EI/L^3, \quad \text{and} \quad m_2 = m/2.63$$

As a result, the frequency " ω_2 " of the expansive vibration in the same phase mode can be shown by the following equation (2).

$$\omega_2^2 = (SE/L + 12EI/L^3)/(M + m/3 + m/2.63) \quad \cdots (2)$$

3. A condition for making the trail of the chip member be circular is described below. As mentioned above, it is necessary to coincide the frequency " ω_1 " of the expansive vibration in the same phase mode with the frequency " ω_2 " of the expansive vibration in the opposite phase mode. That is, the following equation will be composed.

$$SE/L(M + m/3) = (SE/L + 12EI/L^3)/(M + m/3 + m/2.63)$$

Hereupon, the equation is simplified by using $S=W \times H$, and $I=WH^3/12$. The symbols "W" and "H" respectively designate the

width and the height of the piezoelectric device. The condition that the frequencies " ω_1 " and " ω_2 " coincide with each other is shown by the following equation (3).

$$M=(L^2/H^2-0.88)\times m/2.63 \quad \cdots(3)$$

It is found that the most suitable mass "M" of the chip member becomes larger, even when the mass "m" of the piezoelectric device is the same but a ratio of the width and the height in a cross-section of the piezoelectric device is larger.

4. Modeling of the expansive vibration in the opposite phase mode under the non-constraint condition is described. When the base member is not constrained, it is necessary to find a node of a vibration which serves as a standard point for obtaining the natural frequency of the actuator. The node is a point where no displacement occurs even when an objective member to be solved is vibrated. The frequencies of both side of the node coincide with each other in the resonance vibration. A first system in which an end of the piezoelectric device is constrained is shown in FIG.13A. A second system in which both ends of the piezoelectric device are constrained is shown in FIG.13B. In the first system shown in FIG.13A, the constrained end of the piezoelectric device becomes the node of the vibration. In the second system shown in FIG.13B, the node is positioned on a center axis of the piezoelectric device, and the frequencies of both side of the node coincide with each other. In comparison with the first system and the second system, the spring

constant becomes double and the mass becomes half in the second system than those in the first system, so that the frequency in the second system becomes double than that in the first system.

Subsequently, the expansive vibration in the opposite phase mode is shown in FIGs.14A and 14B. In FIG.14A, a piezoelectric device disposed substantially horizontal is noticed. The left end of the piezoelectric device is supported on a base member and a chip member is connected to the right end of the piezoelectric device. As shown in FIG.14B, the base member can be regarded as a rotatable rod. Furthermore, an effect owing to another piezoelectric device disposed substantially vertical in FIG.14A can be disregarded. Thus, the vibration system can be shown by a system configured by a spring with a mass and a weight as shown in FIG.14B.

When a mass of the piezoelectric device is designated by a symbol "m", a spring constant of the expansive vibration is designated by a symbol " k_1 ", and a ratio of a length between the end at the base member side to the node with respect to the total length of the piezoelectric device is designated by a symbol "p" ($0 \leq p \leq 1$), a mass " m_L " and a spring constant " k_L " in the left side of the vibration system from the node, and a mass " m_R " and a spring constant " k_R " in the right side of the vibration system from the node are shown by the following equations.

$$\begin{aligned} m_L &= pm, & k_L &= k_1/p \\ m_R &= (1-p)m, \quad \text{and} \quad k_R &= k_1/(1-p) \end{aligned}$$

Furthermore, when a mass of the chip member is designated by

a symbol " M_c ", a half of a moment of inertia of the base member is designated by a symbol " I_z ", a radius of rotation of the base member is designated by a symbol " R ", a displacement in the left side of the vibration system from the node is designated by a symbol " x_L " and a displacement in the right side of the vibration system from the node is designated by a symbol " x_R ", the energies are shown by the following equations.

$$(1/2)k_L x_L^2 = (1/2)I_z (d(x_L/R)/dt)^2 + (1/2)(m_L/3)(dx_L/dt)^2$$

$$(1/2)k_R x_R^2 = (1/2)M_c (dx_R/dt)^2 + (1/2)(m_R/3)(dx_R/dt)^2$$

Hereupon, $x_L = x_L \cos \omega t$ and $x_R = x_R \cos \omega t$ are assumed and substituted in the above-mentioned equations, the frequencies " ω_L " in the left side and " ω_R " in the right side of the vibration system are shown by the following equations (4).

$$\omega_L^2 = (k_1/p)/(I_z/R^2 + pm/3)$$

$$\omega_R^2 = (k_1/(1-p))/(M_c + (1-p)m/3) \quad \cdots (4)$$

Since the frequencies " ω_L " and " ω_R " are the same with respect to the node in the resonance vibration, so that the equations (4) can be deformed as the following equation.

$$(k_1/p)/(I_z/R^2 + pm/3) = (k_1/(1-p))/(M_c + (1-p)m/3)$$

Thus, the position of the node can be obtained by the following equation (5).

$$p = (M_c + m/3)/(M_c + I_z/R^2 + 2m/3) \quad \cdots (5)$$

When the position " p " obtained from the equation (5) is substituted into the equation (4), the natural frequency of the actuator in the opposite phase mode can be obtained.

5. Modeling of the expansive vibration in the same phase mode under the non-constraint condition is described. The expansive vibration in the same phase mode is shown in FIGs.15A to 15C. In FIG.15A, a piezoelectric device disposed substantially horizontal is noticed. The left end of the piezoelectric device is supported on a base member, a chip member is connected to the right end of the piezoelectric device, and another piezoelectric device is further provided between the chip member and the base member. The base member can be regarded as a cantilever bottom of which is supported. Each piezoelectric device can be regarded as a half of a beam both ends of which are supported.

When a ratio of lengths of the piezoelectric devices are designated by a symbol "q" ($0 \leq q \leq 1$), a spring constant of the bending vibration is designated by a symbol " k_2 ", an equivalent mass of the base member is designated by a symbol " M_b ", and a spring constant of a bending deformation of the piezoelectric device is designated by a symbol " k_3 ", the frequencies " ω_L " in the left side and " ω_R " in the right side of the vibration system are shown by the following equations (6).

$$\begin{aligned}\omega_L^2 &= (k_1/q + k_2)/(M_b' + qm/3) \\ \omega_R^2 &= (k_1/(1-q) + k_3)/(M_c + (1-q)m/3 + m/2) \quad \cdots (6)\end{aligned}$$

Since the frequencies " ω_L " and " ω_R " are the same with respect to the node in the resonance vibration, so that the equations (6) can be deformed as the following equation (7).

$$(k_1/q+k_2)/(M_b'+qm/3)=(k_1/(1-q)+k_3)/(M_c+(1-q)m/3+m/2) \quad \cdots (7)$$

The above-mentioned equation (7) is a cubic equation with respect to "q", so that it is generally difficult to solve the equation. When a suitable value is substituted into "q" in a range of $0 \leq q \leq 1$, it is found that the equation (7) can be approximated by the following equation (8). A symbol "N" designates a constant.

$$M_c+5m/6 \doteq qN/(1-q) \quad \cdots (8)$$

The value "N" is obtained by deforming the equation (8).

$$N=(M_b'+mq/3) \times (k_1+(1-q)k_3)/(k_1+k_2q)+m(1-q)/3$$

When it is assumed that $k_1 \gg k_2$ and k_3 , the above-mentioned equation becomes as the following equation.

$$\begin{aligned} N &\doteq (M_b'+mq/3)+m(1-q)/3 \\ &= M_b'+m/3 \end{aligned}$$

When the value of "N" is substituted into the equation (8), the position of the node in the same phase mode can be obtained by the following equation (9).

$$\begin{aligned} q &= (M_c+5m/6)/(M_c+5m/6+M_b'+m/3) \\ &= (M_c+5m/6)/(M_c+M_b'+7m/6) \quad \cdots (9) \end{aligned}$$

When the position "q" obtained from the equation (9) is substituted into the equation (6), the natural frequency of the actuator in the same phase mode can be obtained.

MODIFICATIONS

The piezoelectric device is electrically equivalent to a capacitor. When the frequency of the driving signals becomes close to the resonance frequency, the phase difference between the phase of

the voltage of the driving signals supplied to the piezoelectric device and the phase of the current flowing in the piezoelectric device varies. The displacement of the piezoelectric device can be regarded to be equivalent to the current flowing therein. Thus, when there is a difference between the resonance frequencies of two piezoelectric devices, the phase difference between the driving signals cannot be reflected to the trail of the chip member accurately. Furthermore, a difference occurs between the displacements of the piezoelectric devices corresponding to the frequency of the driving signals. Thus, the trail of the chip member cannot be formed as the desired shape.

For solving these problems, the currents flowing in mechanical arms of two piezoelectric devices are sensed, and the amplitude of the voltage of the driving signals are controlled so that the amplitudes of the vibration of the piezoelectric devices are the same. Furthermore, the phase difference of the voltages of the driving signals is controlled so that the phase difference between the phases of the currents flowing in the piezoelectric devices are to be a predetermined value, for example, 90 degrees. As a result, the trail of the chip member can be controlled to be a desired elliptic or circular shape.

An equivalent circuit of the piezoelectric device is shown in FIG.16. The displacement of the piezoelectric device is in proportion to a value of a current flowing in the mechanical arm. However, the value of the current is actually sensed from a voltage between both ends of the resistor "Ra", so that it is necessary to subtract a value of the current flowing in the electric arm from the

value sensed by the resistor "Ra". A capacitance "C" of the electric arm can be measured previously, and the value of the capacitance "C" can be regarded as constant. Since the value of the current flowing in the electric arm can be known from the voltage of the driving signals applied to the piezoelectric device, the value of the current flowing in the mechanical arm can be known by subtracting the value of the current flowing in the electric arm from the value of the current flowing in the resistor "Ra".

A block diagram of a modified driving circuit is shown in FIG.17. An oscillator 50 generates sine wave signals having a predetermined frequency. The frequency of the sine wave signals is variable corresponding to the variation of the resonance frequency due to the variation of the circumstances. A phase controller 51 controls a delay circuit 52 corresponding to rotation speed, driving torque, rotation direction of the rotor 40 so as to generate sine wave signals having a predetermined phase difference. An amplitude controller 53 controls a first amplifier 54 and a second amplifier 55 for amplifying two sine wave signals having a phase difference. The amplified sine wave signals by the first amplifier 54 and the second amplifier 55 are respectively applied to the first piezoelectric device 10 and the second first piezoelectric device 10'. A first current sensor 56 senses a value of a current flowing in the mechanical arm of the first piezoelectric device 10. A second current sensor 57 senses a value of a current flowing in the mechanical arm of the second piezoelectric device 10'. The sensing results of the first current

sensor 56 and the second current sensor 57 are inputted to the phase controller 51 and the amplitude controller 53. The phase controller 51 further detects a phase difference between the phase of the current flowing in the mechanical arm of the first piezoelectric device 10 and the phase of the current flowing in the mechanical arm of the second piezoelectric device 10' from the signals from the first current sensor 56 and the second current sensor 57, and controls the delay circuit 52 so that the phase difference between the currents becomes a predetermined value. The amplitude controller 53 further detects an amplitude of the current flowing in the mechanical arm of the first piezoelectric device 10 and an amplitude of the current flowing in the mechanical arm of the second piezoelectric device 10' from the signals from the first current sensor 56 and the second current sensor 57, and controls the first amplifier 54 and the second amplifier 55 so that the amplitudes of the currents become predetermined values.

Subsequently, the resonance characteristics of the piezoelectric device are described. FIG.18A shows a relation between the variation of the impedance of the piezoelectric device and the frequency of the driving signals. Hereinafter, the frequency of the driving signals is abbreviated as "frequency". FIG.18B shows the phase difference between the phase of the current flowing in the mechanical arm of the piezoelectric device and the frequency. FIG.18C shows a relation between the displacement of the piezoelectric device and the frequency. In FIGs.18A to 18C, the abscissa shows the frequency "f".

In the figures, it is noticed from the left side to the right side. When the frequency is gradually increased, the impedance of the piezoelectric device decreases and the displacement of the piezoelectric device increases corresponding to the increase of the frequency. With respect to the phase difference between the phase of the voltage of the driving signals and the phase of the current flowing in the mechanical arm (hereinafter, abbreviated as "phase difference between the voltage and the current"), the phase of the current generally advances 90 degrees. However, when the frequency " f " approaches to the resonance frequency " f_r ", the phase difference between the voltage and the current abruptly decreases. When the frequency " f " reaches to the resonance frequency " f_r ", the impedance of the piezoelectric device becomes the smallest value, and the phase difference between the voltage and the current becomes "0". Furthermore, the displacement of the piezoelectric device becomes the largest.

When the frequency " f " becomes a little larger than the resonance frequency " f_r ", the impedance of the piezoelectric device abruptly increases, and the phase of the current becomes to be delayed from the phase of the voltage. The displacement of the piezoelectric device becomes gradually smaller than the largest value at the resonance frequency " f_r ". When the frequency " f " becomes larger, the phase difference between the voltage and the current becomes substantially constant in a frequency band. Hereinafter, the frequency band in which the phase difference between the voltage and

the current becomes substantially constant is called "stable frequency band".

When the frequency " f " becomes much larger, the phase difference between the voltage and the current decreases. When the frequency " f " reaches to the antiresonance frequency " f_z ", the phase difference between the voltage and the current becomes "0". Simultaneously, the impedance of the piezoelectric device becomes the largest value. When the frequency " f " becomes larger than the antiresonance frequency " f_z ", the impedance of the piezoelectric device gradually decreases, and the phase of the current advances than the phase of the voltage. The phase difference between the voltage and the current will be stabilized in a state that the phase of the current advances 90 degrees than the phase of the voltage.

As mentioned above, the phase difference between the phase of the voltage of the driving signals and the phase of the current flowing in the mechanical arm is abruptly varied in the vicinity of the resonance frequency " f_r ".

Subsequently, an example for driving the actuator so as to move the chip member 20 along a circular trail is considered. When the resonance frequency of the first piezoelectric device 10 coincides with that of the second piezoelectric device 10' and the impedance of them are substantially the same, the displacement and the phases of the voltage and the current of the first piezoelectric device 10 are varied similar to those of the second piezoelectric device 10' even when the frequency of the driving signals is varied in the vicinity of

the resonance frequency. Thus, when the frequency of the driving signals is set to be the same as the resonance frequency of the piezoelectric devices, the amplitudes of the voltages of the driving signals applied to the first piezoelectric device 10 and the second piezoelectric device 10' are set to be the same, and the phase difference between the driving signals applied to the first piezoelectric device 10 and the second piezoelectric device 10' is maintained to be 90 degrees, the trail of the chip member 20 can be made circular having the largest diameter as shown in FIG.20A. The waveforms of the voltages of the driving signals and the currents flowing in the first piezoelectric device 10 and the second piezoelectric device 10' are shown in FIG.21A.

The resonance frequencies and the impedance characteristics of the first piezoelectric device 10 and the second piezoelectric device 10', however, are not necessarily the same, because of the variation and the error components in the manufacturing process of the piezoelectric devices and in the assembling process of the actuator. FIGs.19A to 19C show the resonance characteristics of two piezoelectric devices respectively having different resonance frequencies and the impedance characteristics. FIG.19A corresponds to FIG.18A, FIG.19B corresponds to FIG.18B, and FIG.19C corresponds to FIG.18C. In FIGs.19A to 19C, the characteristic curves illustrated by solid lines show the resonance characteristics of the first piezoelectric device 10, and the characteristic curves illustrated by dotted lines show the resonance characteristics of the

second piezoelectric device 10'.

In the figures, the resonance frequency " f_a " of the first piezoelectric device 10 is noticed. The phase difference of the voltage and the current with respect to the first piezoelectric device 10 is "0". On the other hand, the frequency " f_a " is smaller than the resonance frequency " f_b " of the second piezoelectric device 10'. The phase of the current advances about 60 degrees than the frequency of the voltage with respect to the second piezoelectric device 10'.

When the driving signals having the waveforms shown by "VOLTAGE" in FIG.21B, in which the phase of the driving signal applied to the first piezoelectric device 10 advances 90 degrees than that applied to the second piezoelectric device 10', are applied to the first piezoelectric device 10 and the second piezoelectric device 10' having the above-mentioned resonance characteristics, the phase difference between the phase of the current flowing in the mechanical arm of the first piezoelectric device 10 and that of the second piezoelectric device 10' becomes about 30 degrees. Thus, the trail of the chip member 20 becomes an ellipse having the major axis parallel to the symmetry axis of the actuator as shown in FIG.20B.

On the contrary, when the driving signals having the waveforms shown by "VOLTAGE" in FIG.21C, in which the phase of the driving signal applied to the second piezoelectric device 10' advances 90 degrees than that applied to the first piezoelectric device 10, are applied to the first piezoelectric device 10 and the second piezoelectric device 10', the phase difference between the phase of the

current flowing in the mechanical arm of the first piezoelectric device 10 and that of the second piezoelectric device 10' becomes about 150 degrees. Thus, the trail of the chip member 20 becomes an ellipse having the minor axis parallel to the symmetry axis of the actuator as shown in FIG.20C. As a result, the rotation speed of the chip member 20 or the rotor 40 is different corresponding to the rotation directions.

For solving this problem, a first method is proposed for driving the first piezoelectric device 10 and the second piezoelectric device 10' by driving signals having a frequency " f_i " at which the phase difference of the voltage and the current with respect to the first piezoelectric device 10 coincides with the phase difference of the voltage and the current with respect to the second piezoelectric device 10'. As mentioned above, the stable frequency band in which the phase difference between the voltage and the current becomes substantially constant and stable is exist between the resonance frequency and the antiresonance frequency of the piezoelectric devices. When FIG.19B is noticed, it is found that the stable frequency band with respect to the first piezoelectric device 10 overlaps the stable frequency band with respect to the second piezoelectric device 10' in the vicinity of the frequency " f_i ".

Thus, when the driving signals having the frequency of the driving signals " f_i " and the phase difference of 90 degrees are applied to the first piezoelectric device 10 and the second piezoelectric device 10', the phase difference between the phase of the current flowing in

the mechanical arm of the first piezoelectric device 10 and that of the second piezoelectric device 10' can be made 90 degrees. Since the resonance frequency " f_a " of the first piezoelectric device 10 is different from the resonance frequency " f_b " of the second piezoelectric device 10', the displacement of the first piezoelectric device 10 is a little different from the displacement of the second piezoelectric device 10'. In comparison with a case for driving the first piezoelectric device 10 and the second piezoelectric device 10' by driving signals having the resonance frequency " f_a " or " f_b " of any piezoelectric device, the difference between the displacement of the first piezoelectric device 10 and the displacement of the second piezoelectric device 10' is smaller (see FIG.19C). Thus, the trail of the chip member 20 can be made substantially circular, and there is no problem in the actual use.

A block diagram of the driving circuit suitable for the first method is shown in FIG.22. An oscillator 50 generates sine wave signals having a predetermined frequency. The frequency of the sine wave signals is variable. A delay circuit 52 generates sine wave signals the phase of which is delayed at a predetermined angle such as 90 degrees with respect to the sine wave signals from the oscillator 50. A first amplifier 54 and a second amplifier 55 amplify two sine wave signals having the phase difference, and apply the amplified sine wave signals to the first piezoelectric device 10 and the second first piezoelectric device 10'. A first current sensor 56 senses a value of a current flowing in the mechanical arm of the first piezoelectric device

10. A second current sensor 57 senses a value of a current flowing in the mechanical arm of the second piezoelectric device 10'. The sensing results of the first current sensor 56 and the second current sensor 57 are inputted to the oscillator 50. The oscillator 50 searches the overlapped band of the stable frequency band with respect to the first piezoelectric device 10 and the stable frequency band with respect to the second piezoelectric device 10' from the current signals from the first current sensor 56 and the second current sensor 57. Furthermore, the oscillator 50 decides the frequency " f_i " of the driving signals. When the frequency " f_i " of the driving signals is decided, the oscillator 50 continues to oscillate the sine wave signals at the frequency " f_i ".

As a method for deciding the frequency " f_i " of the driving signals, the frequency of the oscillation of the oscillator 50 is gradually varied and the resonance frequency " f_a " of the first piezoelectric device 10 and the antiresonance frequency " f_b " of the second piezoelectric device 10' are detected from the current signals from the first current sensor 56 and the second current sensor 57 and the voltage of the driving signals. The frequency " f_i " of the driving signals is decided to be the center value between the resonance frequency " f_a " of the first piezoelectric device 10 and the antiresonance frequency " f_b " of the second piezoelectric device 10'. Alternatively, the frequencies in the vicinity of the frequency at which the phase difference of the voltage and the current with respect to the first piezoelectric device 10 are compared with those with respect to

the second piezoelectric device 10' by varying the frequency of the oscillation of the oscillator 50. The frequency " f_i " of the driving signals is selected to be one of the frequency commonly included in the frequencies with respect to the first piezoelectric device 10 and the frequencies with respect to the second piezoelectric device 10'.

When the driving circuit shown in FIG.22 is compared with the driving circuit shown in FIG.17, the phase controller 51 and the amplitude controller 53 are not necessary, so that the configuration of the driving circuit can be simplified. Furthermore, the amplitude of the voltage and the phase difference of the driving signals are not adjusted, so that the control of the actuator can be simplified.

Still furthermore, the phase difference of the voltage and the current is stable in the vicinity of the frequency " f_i ". Thus, it is possible to maintain the shape of the trail of the chip member by driving the piezoelectric devices continuously at a predetermined frequency " f_i " of the driving signals, since the variation of the phase difference between the voltage and the current is smaller when the variation of the resonance frequencies of the piezoelectric devices due to the variation of circumstances is small. In this case, the adjustment of the frequency of the oscillation by the oscillator 50 and the detection of the currents by the first current sensor 56 and the second current sensor 57 can be omitted, and the configuration of the driving circuit can be made more simple.

Subsequently, a second method for solving the above-mentioned problem is proposed for driving the first piezoelectric

device 10 and the second piezoelectric device 10' by driving signals having a frequency " f_e " between the resonance frequency " f_a " of the first piezoelectric device 10 and the resonance frequency " f_b " of the second piezoelectric device 10', at which the displacement of the first piezoelectric device 10 coincides with the displacement of the second piezoelectric device 10'. As mentioned above, the displacement of the piezoelectric device becomes the largest value when the frequency of the driving signal coincides with the resonance frequency of the piezoelectric device, but it decreases when the frequency of the driving signal is a little larger or smaller than the resonance frequency. Thus, the frequency " f_e " at which the displacement of the first piezoelectric device 10 coincides with the displacement of the second piezoelectric device 10' exists in a frequency band between the resonance frequency " f_a " of the first piezoelectric device 10 and the resonance frequency " f_b " of the second piezoelectric device 10'. The currents flowing in the mechanical arms of the first piezoelectric device 10 and the second piezoelectric device 10' are sensed and the frequency " f_e " at which the current values becomes the same is found. The first piezoelectric device 10 and the second piezoelectric device 10' are driven by the driving signals having the frequency " f_e ". In this case, since the frequency " f_e " of the driving signals is different from the resonance frequency " f_a " of the first piezoelectric device 10 and the resonance frequency " f_b " of the second piezoelectric device 10', it is necessary to adjust the phase difference of the voltages of the driving signals so that the phase difference between the phase of the

current flowing in the mechanical arm of the first piezoelectric device 10 and the phase of the current flowing in the mechanical arm of the second piezoelectric device 10' becomes 90 degrees.

A block diagram of the driving circuit suitable for the second method is shown in FIG.23. An oscillator 50 generates sine wave signals having a predetermined frequency. The frequency of the sine wave signals is variable. A phase controller 51 controls a delay circuit 52 so as to generate sine wave signals having a predetermined phase difference. A first amplifier 54 and a second amplifier 55 amplify two sine wave signals having the phase difference, and apply the amplified sine wave signals to the first piezoelectric device 10 and the second first piezoelectric device 10'. A first current sensor 56 senses a value of a current flowing in the mechanical arm of the first piezoelectric device 10. A second current sensor 57 senses a value of a current flowing in the mechanical arm of the second piezoelectric device 10'. The sensing results of the first current sensor 56 and the second current sensor 57 are inputted to the oscillator 50 and the phase controller 51. The oscillator 50 searches the frequency " f_e " at which the displacement of the first piezoelectric device 10 coincides with the displacement of the second piezoelectric device 10' in the vicinity of the resonance frequency " f_a " of the first piezoelectric device 10 and the resonance frequency " f_b " of the second piezoelectric device 10' from the current signals from the first current sensor 56 and the second current sensor 57. When the frequency " f_e " of the driving signals is found, the oscillator 50 continues to oscillate the sine wave

signals at the frequency " f_e ". The phase controller 51 controls the delay circuit 52 so that the phase difference between the phase of the current signal from the first current sensor 56 and the phase of the current signal from the second current sensor 57 becomes 90 degrees.

As a method for deciding the frequency " f_e " of the driving signals, the frequency of the oscillation of the oscillator 50 is gradually varied and the frequency " f_e " at which the current value or the amplitude of the current signal from the first current sensor 56 coincides with the current value or the amplitude of the current signal from the second current sensor 57 is found.

When the driving circuit shown in FIG.23 is compared with the driving circuit shown in FIG.17, the amplitude controller 53 is not necessary, so that the configuration of the driving circuit can be simplified. Furthermore, the amplitude of the voltage of the driving signals is not adjusted, so that the control of the actuator can be simplified.

Still another modification of the actuator in this embodiment is described. In this embodiment, the piezoelectric device is used as the displacing device. The ceramics which is a material of the ceramic thin plate 11 has larger damping factor of the vibrations and the smaller magnification factor of the resonant vibration than those of the metal materials. Furthermore, the ceramics is stronger with respect to the pressure but weaker with respect to the tension, so that it will be separated from the adhered faces in the lamination type piezoelectric device. In this modification, a series connection of a

single layered piezoelectric device and an elastic member made of a metal is used as a displacing device.

A configuration of the modified actuator is shown in FIG.24. A first displacing device 60 and a second displacing device 60' are respectively configured by single layered piezoelectric devices (ceramic thin plates) 61 and 61', and elastic members 62 and 62'. No electrode is provided on both surface of the piezoelectric devices 61 and 61'. Base ends of the first displacing device 60 and the second displacing device 60' are respectively fixed on the base member by screws 63 and 63' without using any adhesive. On the other hand, the chip member 20 is connected on top ends of the first displacing device 60 and the second displacing device 60' by an adhesive or screws. The elastic members 62 and 62' and the base member 30 are respectively formed by conductive materials. A driving power source 16 is connected between alternative of elastic members 61 and the base member 30 and the elastic member 62' and the base member 30 so as to drive the first displacing device 60 or the second displacing device 60' at the above-mentioned resonance frequencies.

When the elastic member 62 or 62' is vibrated at the resonance frequency by the piezoelectric device 61 or 61' using as an oscillator, the displacement of the first displacing device 60 or the second displacing device 60' can be enlarged. Furthermore, the tension acting on the piezoelectric devices 61 and 61' becomes smaller, so that the destruction of the piezoelectric device 61 and 61' can be prevented. As a material of the elastic member 62 and 62', aluminum, titanium,

iron, copper, and an alloy including at least one of them can be used. Since the ratio of the piezoelectric devices 61 and 61' in the length of the displacing devices 60 and 60' is very small, the affect due to the piezoelectric devices 61 and 61' can be ignored when the above-mentioned normal vibration is calculated.

In the above-mentioned description of the embodiment, two displacing devices such as the first piezoelectric device 10 and the second piezoelectric device 10' or the first displacing device 60 and the second displacing device 60' are disposed for crossing at right angle. It, however, is not restricted by this disposition. It is possible to cross at another angle such as 45 degrees or 135degrees. Furthermore, the number of the displacing devices are not restricted by two. It is possible to use more than three displacing devices for realizing a movement having three or four degrees of freedom. Still furthermore, it is possible to use another mechanical or electric displacing device such as a magnetostrictive device as a driving source.

Although the present invention has been fully described by way of example with reference to the accompanying drawings, it is to be understood that various changes and modifications will be apparent to those skilled in the art. Therefore, unless otherwise such changes and modifications depart from the scope of the present invention, they should be construed as being included therein.

WHAT IS CLAIMED IS

1. An actuator comprising: a plurality of displacing devices for generating displacements; a compound member connected to the displacing devices and for compounding displacements of the displacing devices; a base member for folding base ends of the displacing devices at which the compound member is not connected; a pressing member for pressing the compound member to an object to be driven; and a driver for resonantly driving the displacing devices so as to move the compound member along an elliptic or a circular trail.

2. The actuator in accordance with claim 1, wherein a natural frequency of the displacing devices in a first natural vibration mode in which the displacing devices are resonantly vibrated in the same phase substantially coincides with a natural frequency of the displacing devices in a second natural vibration mode in which the displacing devices are resonantly vibrated in the opposite phase.

3. The actuator in accordance with claim 2, wherein a mass of the compound member is designated by a symbol "M", a length of the displacing device is designated by a symbol "L", a height of the displacing device is designated by a symbol "H", and a mass of the displacing device is designated by a symbol "m",

$$M=(L^2/H^2-0.88)m/2.63$$

is composed.

4. The actuator in accordance with claim 2, wherein a mass of the compound member is designated by a symbol " M_c ", a mass of each displacing device is designated by a symbol "m", a spring

constant of the displacing device in the expansive deformation is designated by a symbol " k_1 ", a spring constant of the displacing device in the bending deformation is designated by a symbol " k_3 ", a moment of inertia of the base member is designated by a symbol " I_z ", a rotation radius of the base member is designated by a symbol " R ", and an equivalent mass of the base member converted to a cantilever is designated by a symbol " M_b ",

$$(k_1/(1-p))/(M_c+(1-p)m/3)=(k_1/(1-q)+k_3)/(M_c+(1-q)m/3+m/2)$$

$$p=(M_c+m/3)/(M_c+I_z/R^2+2m/3)$$

$$q=(M_c+5m/6)/(M_c+M_b'+7m/6)$$

are composed.

5. The actuator in accordance with claim 1, wherein the displacing device includes an elastic member as a part thereof.

6. An actuator comprising: a first displacing device; a second displacing device; a compound member connected to top ends of the first displacing device and the second displacing device and for compounding displacements of the first displacing device and the second displacing device; and a driver for resonantly driving the displacing devices so as to move the compound member along an elliptic or a circular trail; and wherein

the driver drives the first displacing device and the second displacing device by driving signals respectively having a frequency included in an overlapped region of a first frequency band and a second frequency band;

the first frequency band is defined as a region between the

resonance frequency and the antiresonance frequency of the first displacing device in which a phase difference between a phase of a voltage of the driving signal and a phase of a current flowing in the first displacing device is substantially constant; and

the second frequency band is defined as a region between the resonance frequency and the antiresonance frequency of the second displacing device in which a phase difference between a phase of a voltage of the driving signal and a phase of a current flowing in the second displacing device is substantially constant.

7. The actuator in accordance with claim 6, wherein the frequency of the driving signals is a value at the center between a first frequency and a second frequency; the first frequency is the smaller one of the resonance frequencies of the first displacing device and the second displacing device; and the second frequency is the smaller one of the antiresonance frequencies of the first displacing device and the second displacing device.

8. The actuator in accordance with claim 6, wherein the phase of the driving signal for driving the first displacing device has a phase difference with respect to the driving signal for driving the second displacing device.

9. The actuator in accordance with claim 6, further comprising current sensors respectively for sensing currents flowing in the first displacing device and the second displacing device.

10. An actuator comprising: a first displacing device; a second displacing device; a compound member connected to top ends

of the first displacing device and the second displacing device and for compounding displacements of the first displacing device and the second displacing device; and a driver for resonantly driving the displacing devices so as to move the compound member along an elliptic or a circular trail; and wherein

the driver drives the first displacing device and the second displacing device by driving signals respectively having a frequency included in a frequency band in the vicinity of resonance frequencies of the first displacing device and the second displacing device at which a displacement of the first displacing device is substantially the same as that of the second displacing device.

11. The actuator in accordance with claim 10, wherein a phase difference is provided between the driving signals in a manner so that a current flowing in the first displacing device has a predetermined phase difference with respect to a current flowing in the second displacing device.

12. The actuator in accordance with claim 10, further comprising current sensors respectively for sensing currents flowing in the first displacing device and the second displacing device.

13. A method for driving an actuator comprising: a first displacing device; a second displacing device; a compound member connected to top ends of the first displacing device and the second displacing device and for compounding displacements of the first displacing device and the second displacing device; wherein

the first displacing device and the second displacing device are

driven in a manner so as to move the compound member along an elliptic or a circular trail by using driving signals respectively having a frequency included in an overlapped region of a first frequency band and a second frequency band;

the first frequency band is defined as a region between the resonance frequency and the antiresonance frequency of the first displacing device in which a phase difference between a phase of a voltage of the driving signal and a phase of a current flowing in the first displacing device is substantially constant; and

the second frequency band is defined as a region between the resonance frequency and the antiresonance frequency of the second displacing device in which a phase difference between a phase of a voltage of the driving signal and a phase of a current flowing in the second displacing device is substantially constant.

14. The method for driving the actuator in accordance with claim 13, wherein the frequency of the driving signals is a value at the center between a first frequency and a second frequency; the first frequency is the smaller one of the resonance frequencies of the first displacing device and the second displacing device; and the second frequency is the smaller one of the antiresonance frequencies of the first displacing device and the second displacing device.

15. The method for driving the actuator in accordance with claim 13, wherein the phase of the driving signal for driving the first displacing device has a phase difference with respect to the driving signal for driving the second displacing device.

16. A method for driving an actuator comprising: a first displacing device; a second displacing device; a compound member connected to top ends of the first displacing device and the second displacing device and for compounding displacements of the first displacing device and the second displacing device; wherein

the first displacing device and the second displacing device are driven in a manner so as to move the compound member along an elliptic or a circular trail by using driving signals respectively having a frequency included in a frequency band in the vicinity of resonance frequencies of the first displacing device and the second displacing device at which a displacement of the first displacing device is substantially the same as that of the second displacing device.

17. The method for driving the actuator in accordance with claim 10, wherein a phase difference is provided between the driving signals in a manner so that a current flowing in the first displacing device has a predetermined phase difference with respect to a current flowing in the second displacing device.

ABSTRACT OF THE DISCLOSURE

A truss type actuator including two piezoelectric devices drives a chip member provided at a crossing point of the piezoelectric devices for moving along an elliptic or a circular trail. The piezoelectric devices are respectively driven by driving signals having a frequency equal to or near to the resonance frequency of the piezoelectric devices. By utilizing the resonance phenomenon, the displacements of the piezoelectric device can be increases as larger as possible.



FIG. 3

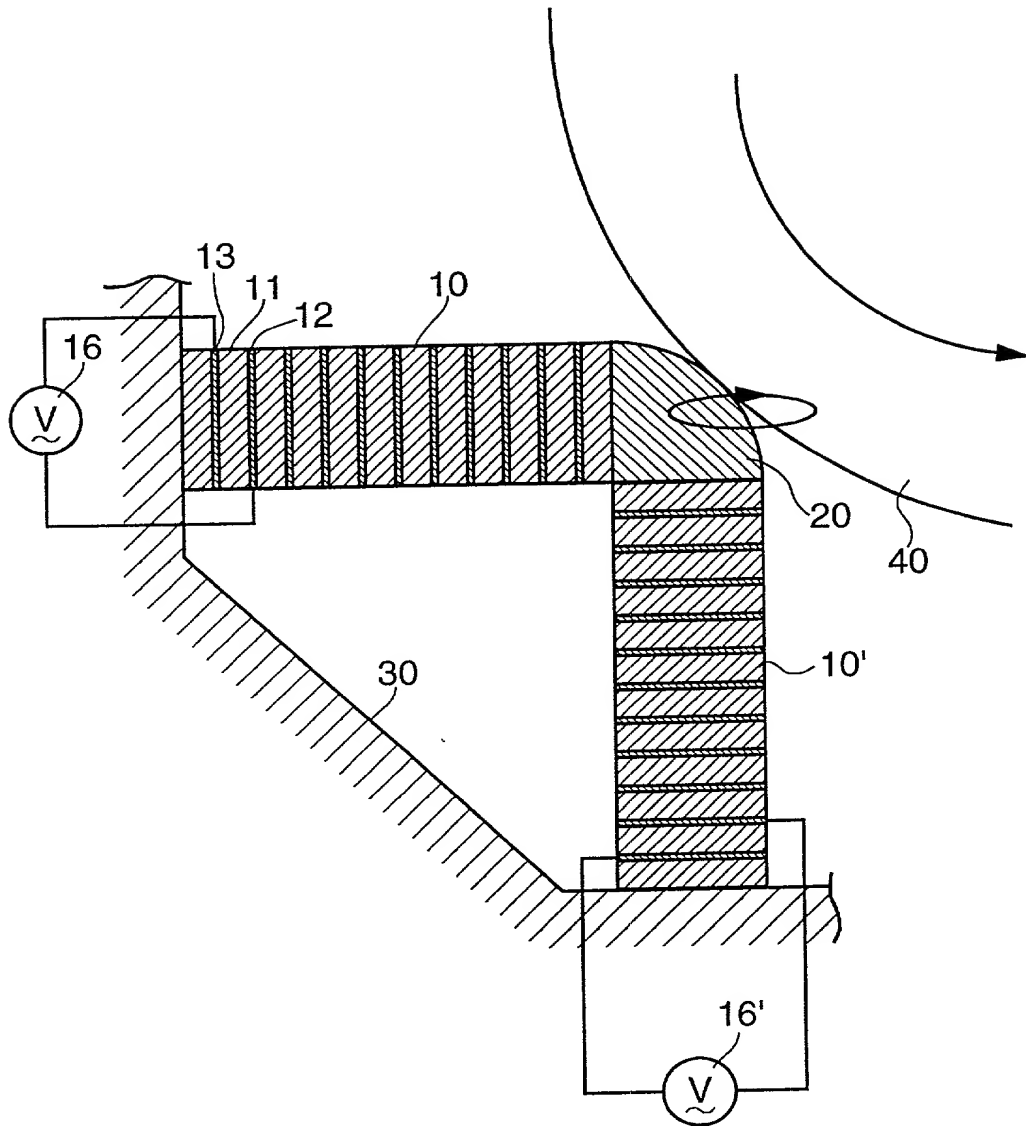


FIG. 4

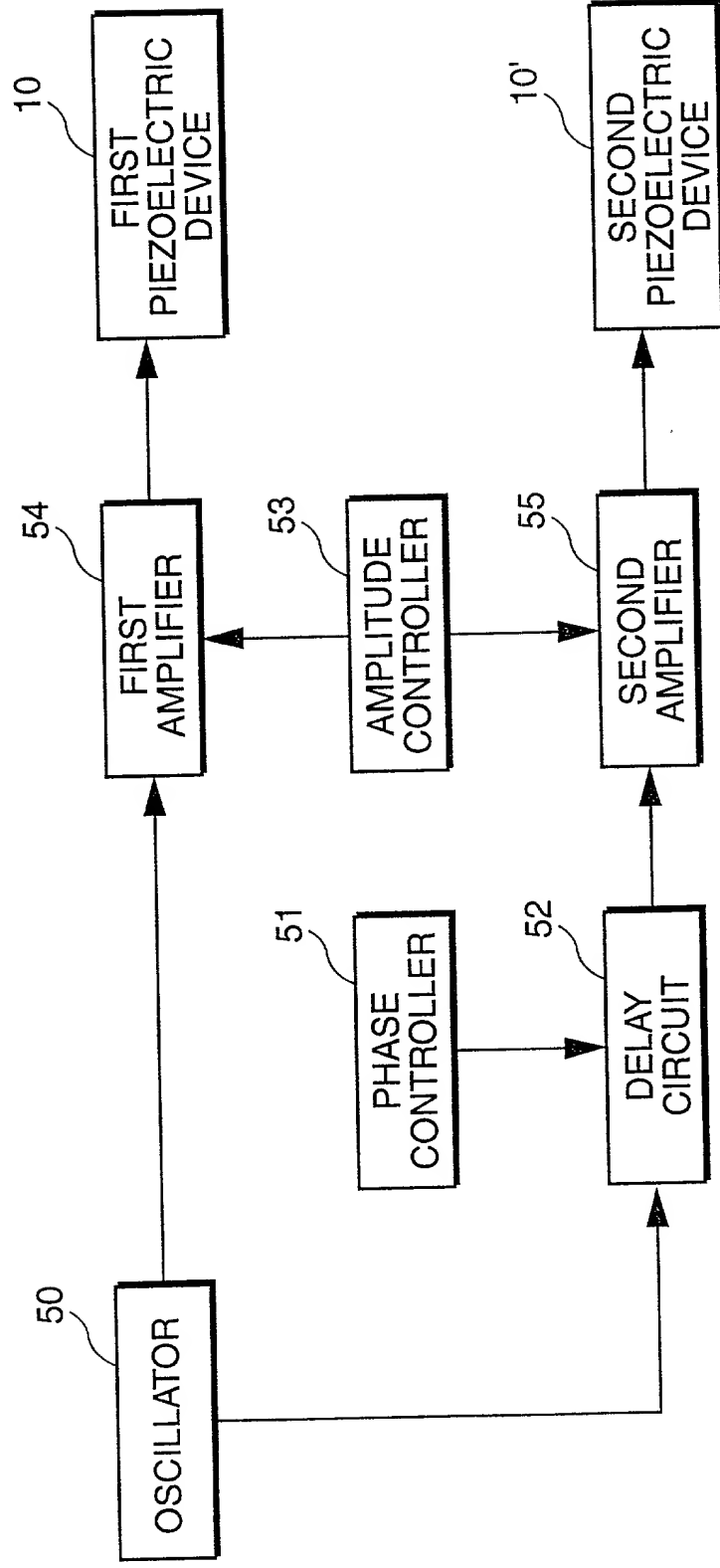


FIG. 5

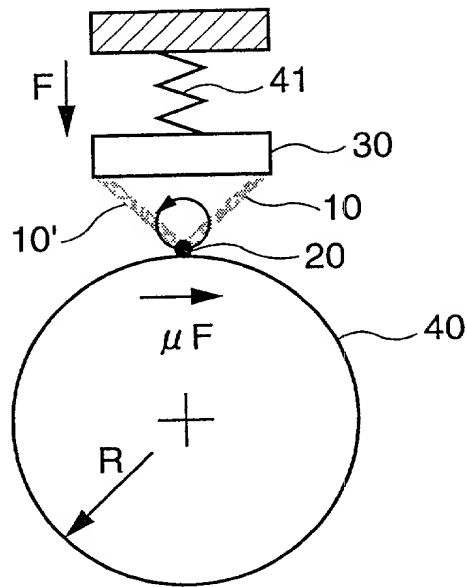


FIG. 6

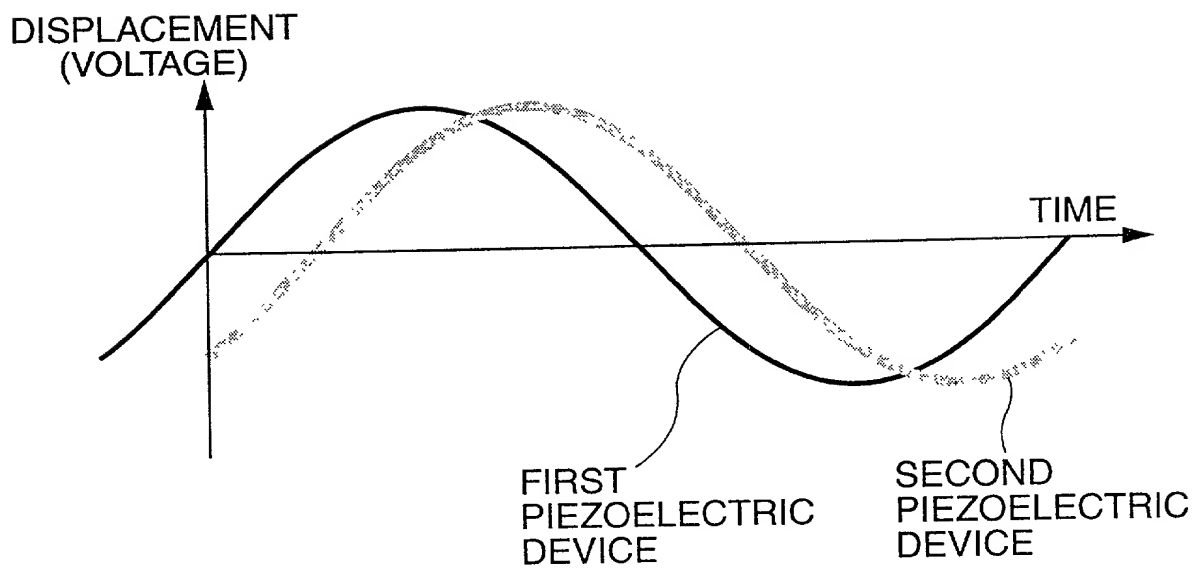


FIG. 7A

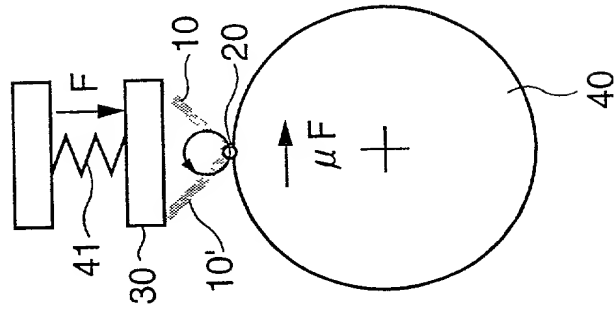


FIG. 7B

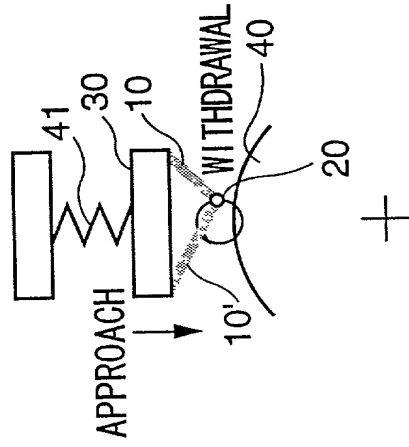


FIG. 7C

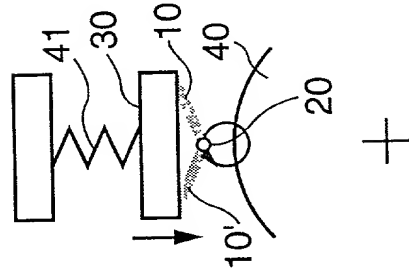


FIG. 7D

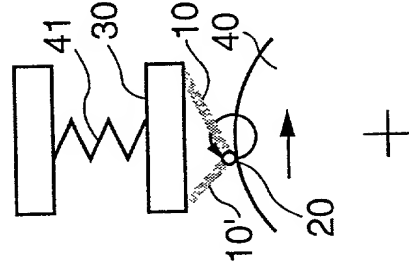


FIG. 7E

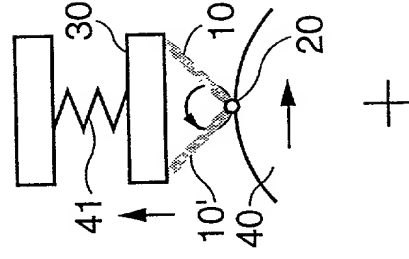


FIG. 8A

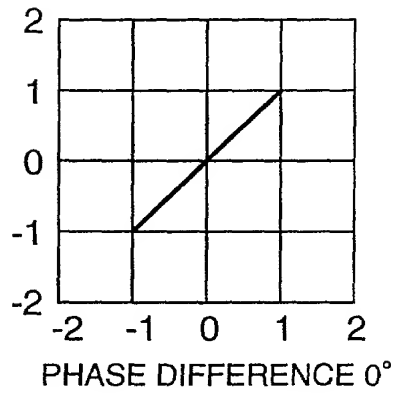


FIG. 8B

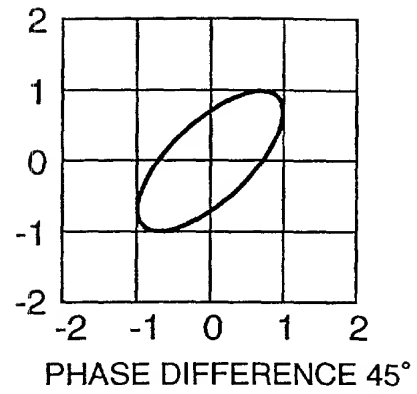


FIG. 8C

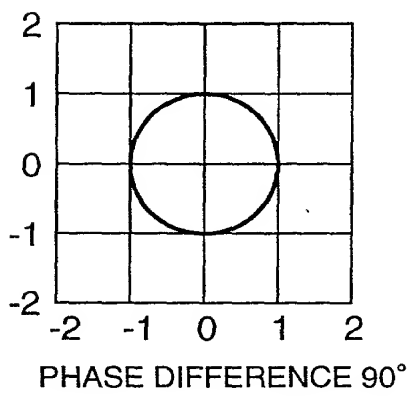


FIG. 8D

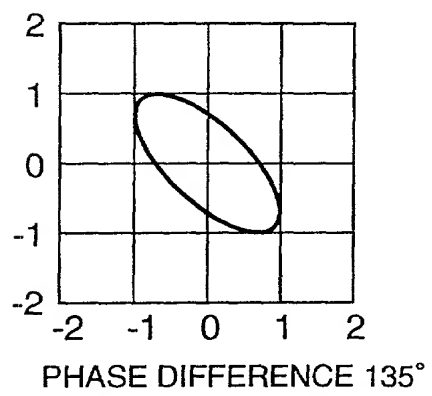


FIG. 8E

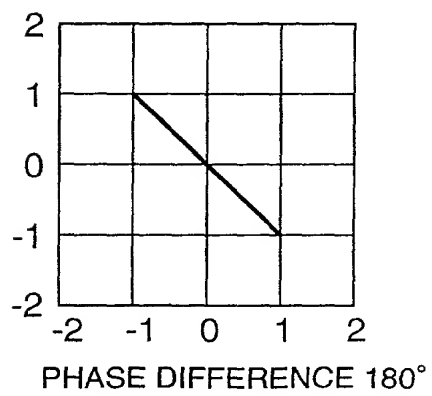


FIG. 9A

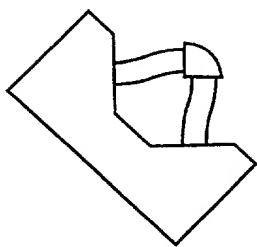


FIG. 9B

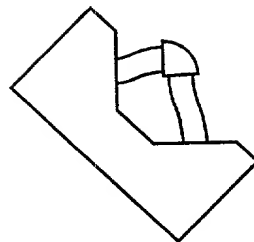


FIG. 9C

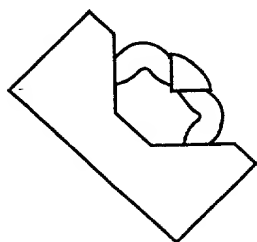


FIG. 9D

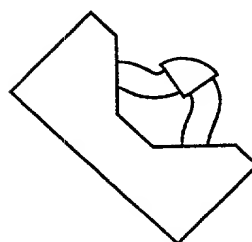


FIG. 10A

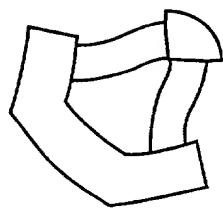


FIG. 10B

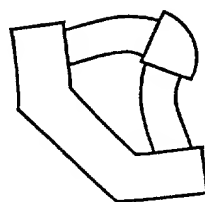


FIG. 10C

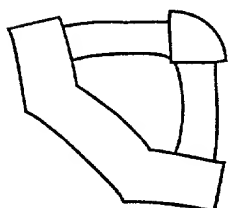


FIG. 10D

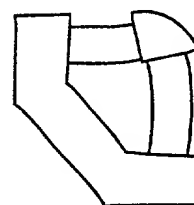


FIG. 11

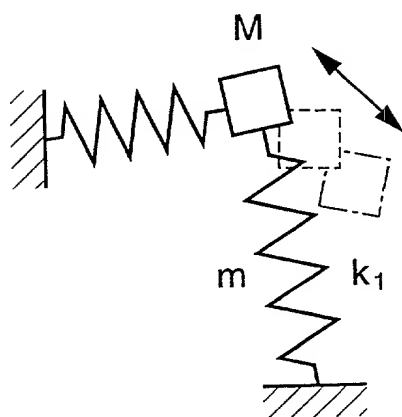


FIG. 12

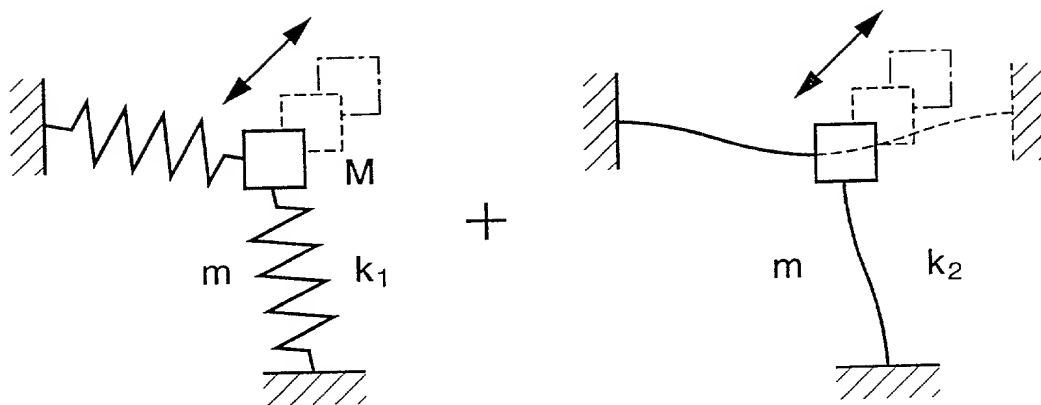
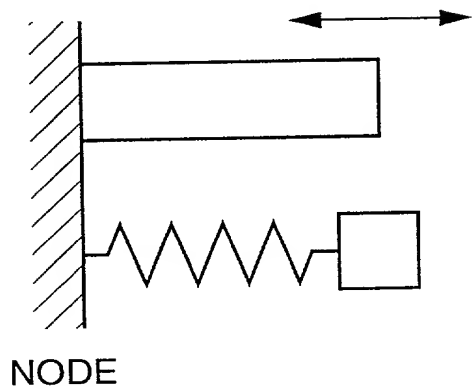


FIG. 13A

AN END CONSTRAINED

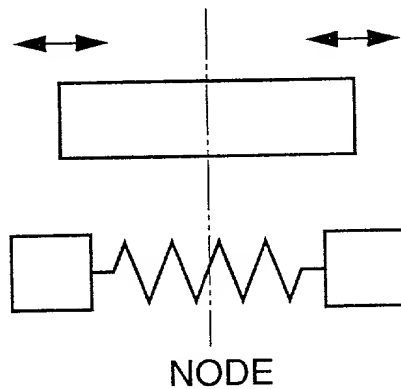


SPRING CONSTANT : $k = SE/L$
 MASS : m
 ANGULAR FREQUENCY : $\omega^2 = k/(m/3)$

S : CROSS-SECTIONAL AREA
 L : LENGTH

FIG. 13B

BOTH ENDS FREE



$$k' = SE/(L/2) \\ = 2k$$

$$m' = m/2$$

$$\omega'^2 = k'/(m'/3) \\ = (2\omega)^2$$

FIG. 14A

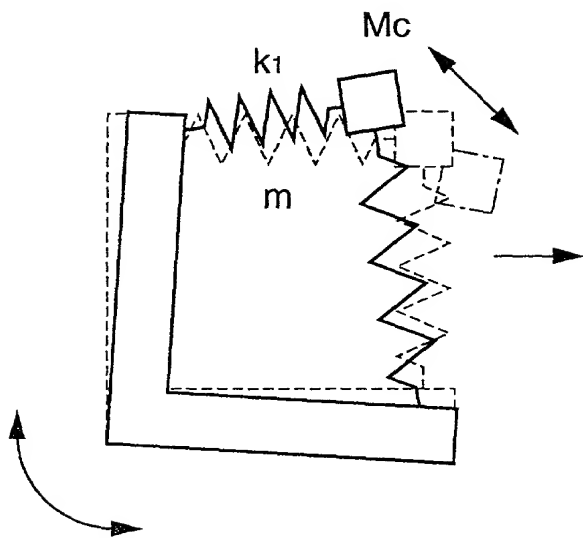


FIG. 14B

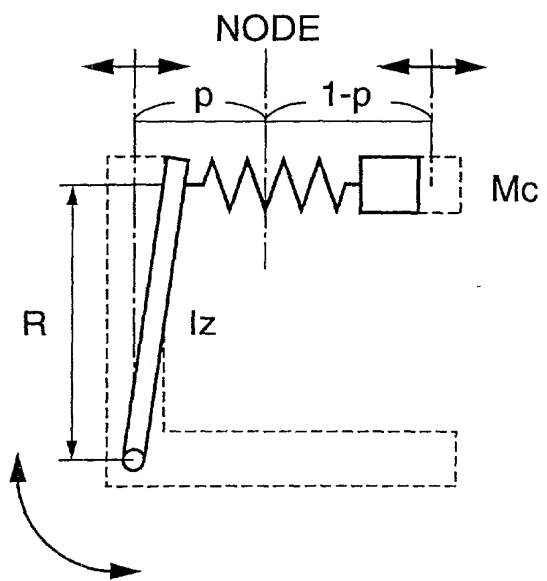


FIG. 15A

EXPANSIVE MOTION

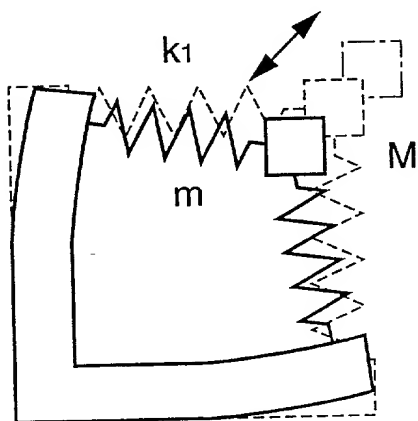


FIG. 15B

EXPANSIVE MOTION

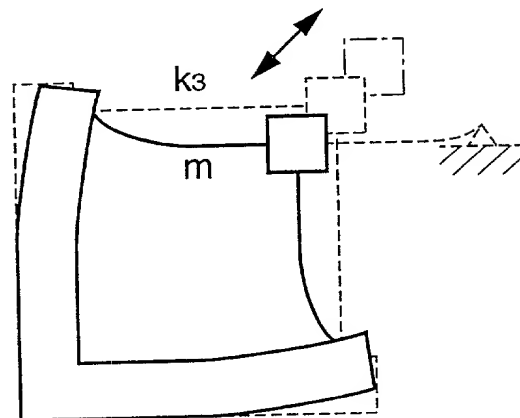


FIG. 15C

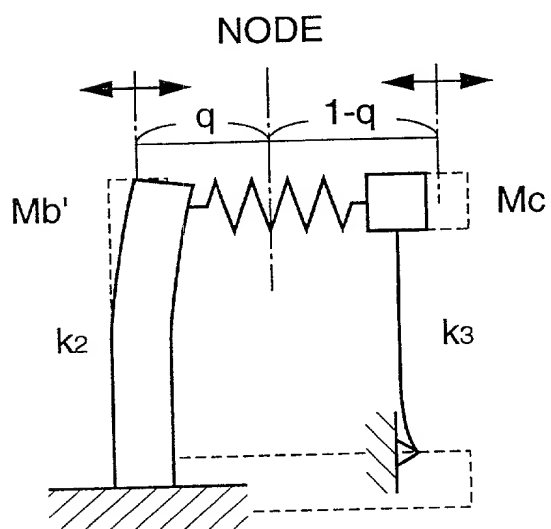


FIG.16

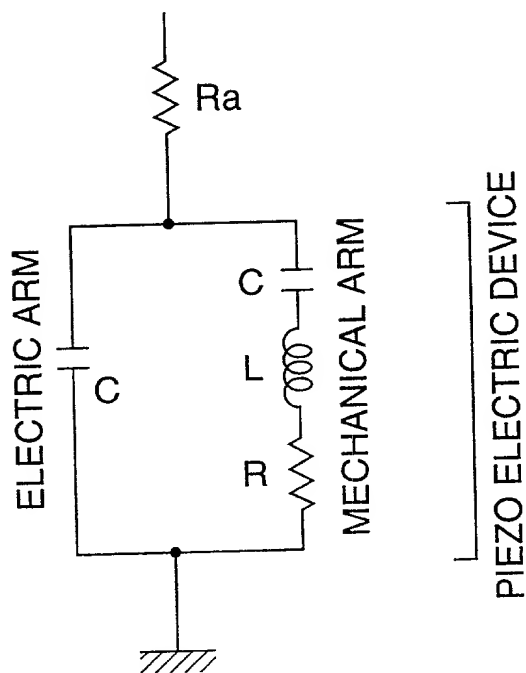


FIG. 18A

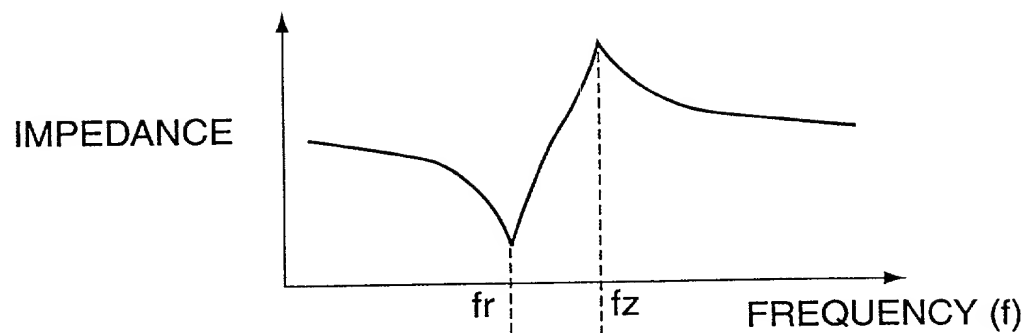


FIG. 18B

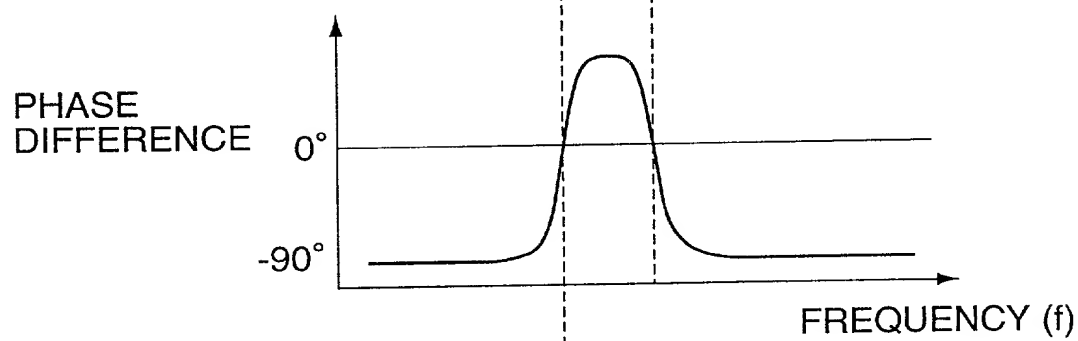


FIG. 18C

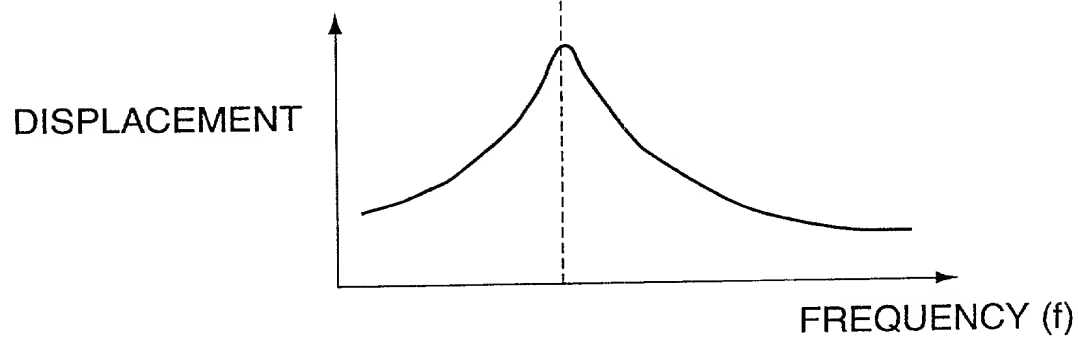


FIG. 19A

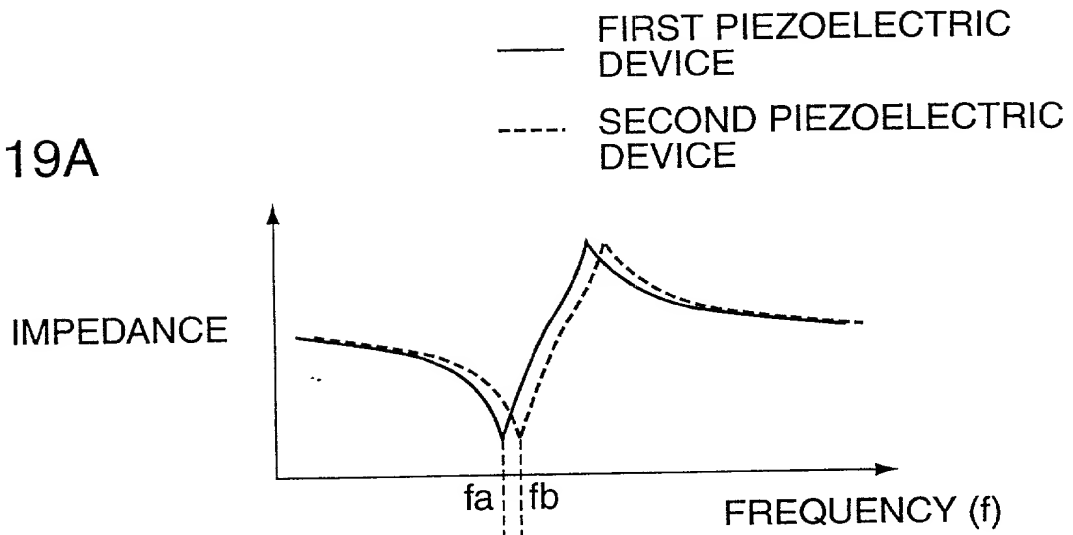


FIG. 19B

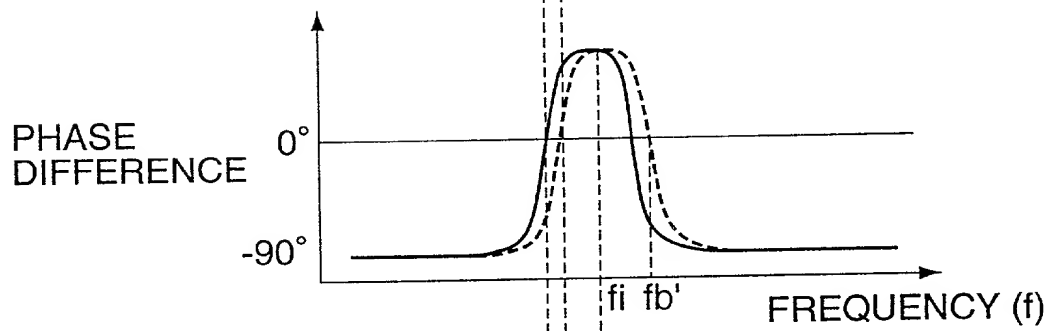
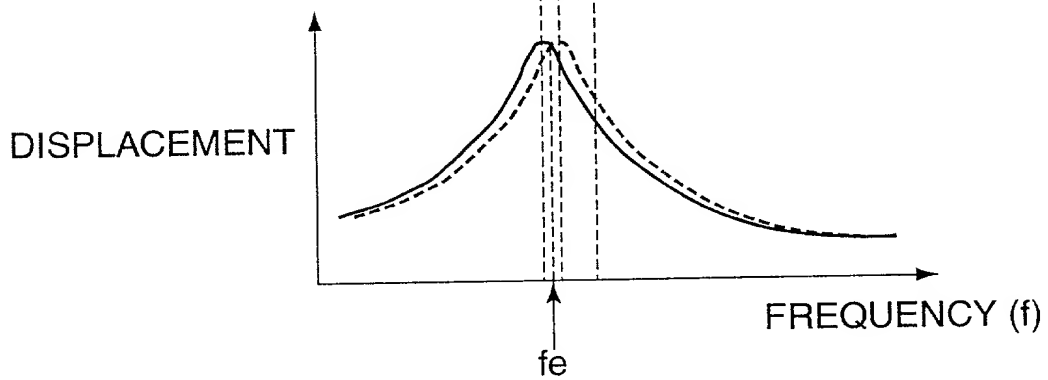


FIG. 19C



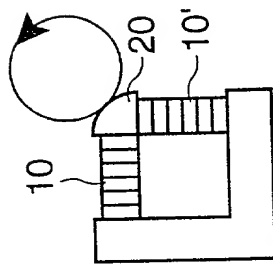


FIG. 20A

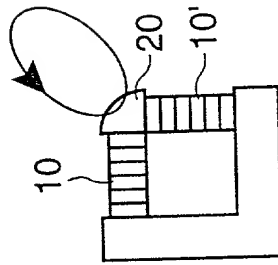


FIG. 20B

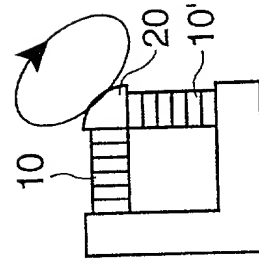


FIG. 20C

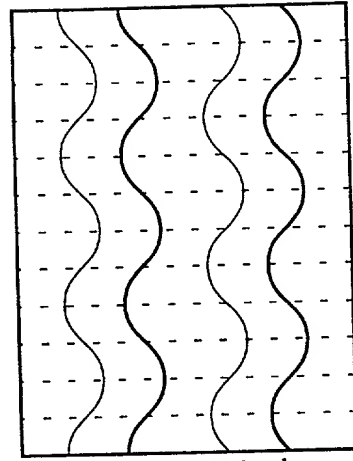


FIG. 21A

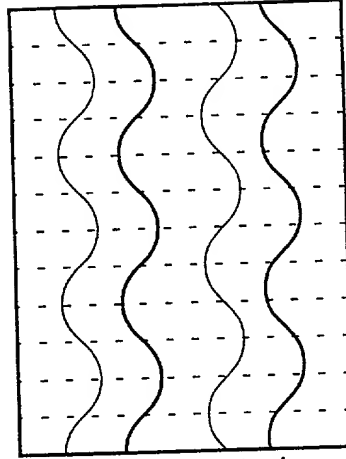


FIG. 21B

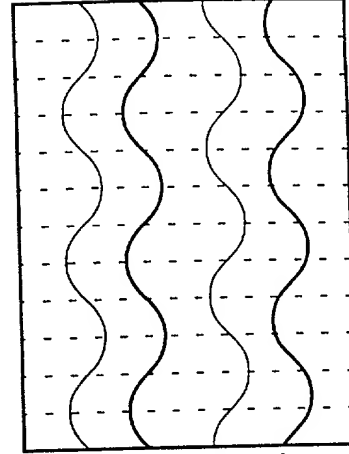






FIG. 21C

FIRST PIEZOELECTRIC DEVICE	VOLTAGE CURRENT	SECOND PIEZOELECTRIC DEVICE	VOLTAGE CURRENT

FIRST PIEZOELECTRIC DEVICE	VOLTAGE CURRENT	SECOND PIEZOELECTRIC DEVICE	VOLTAGE CURRENT
			

FIRST PIEZOELECTRIC DEVICE	VOLTAGE CURRENT	SECOND PIEZOELECTRIC DEVICE	VOLTAGE CURRENT

FIG. 22

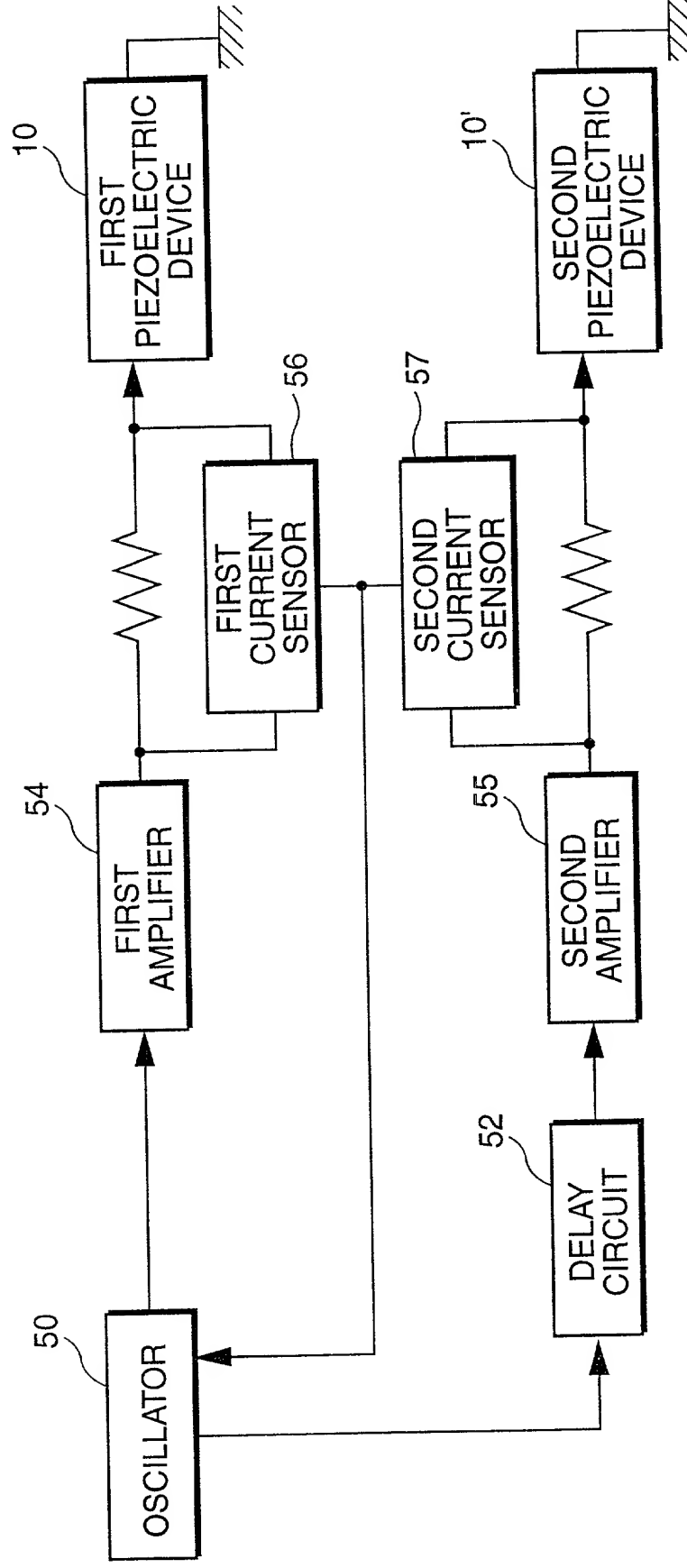
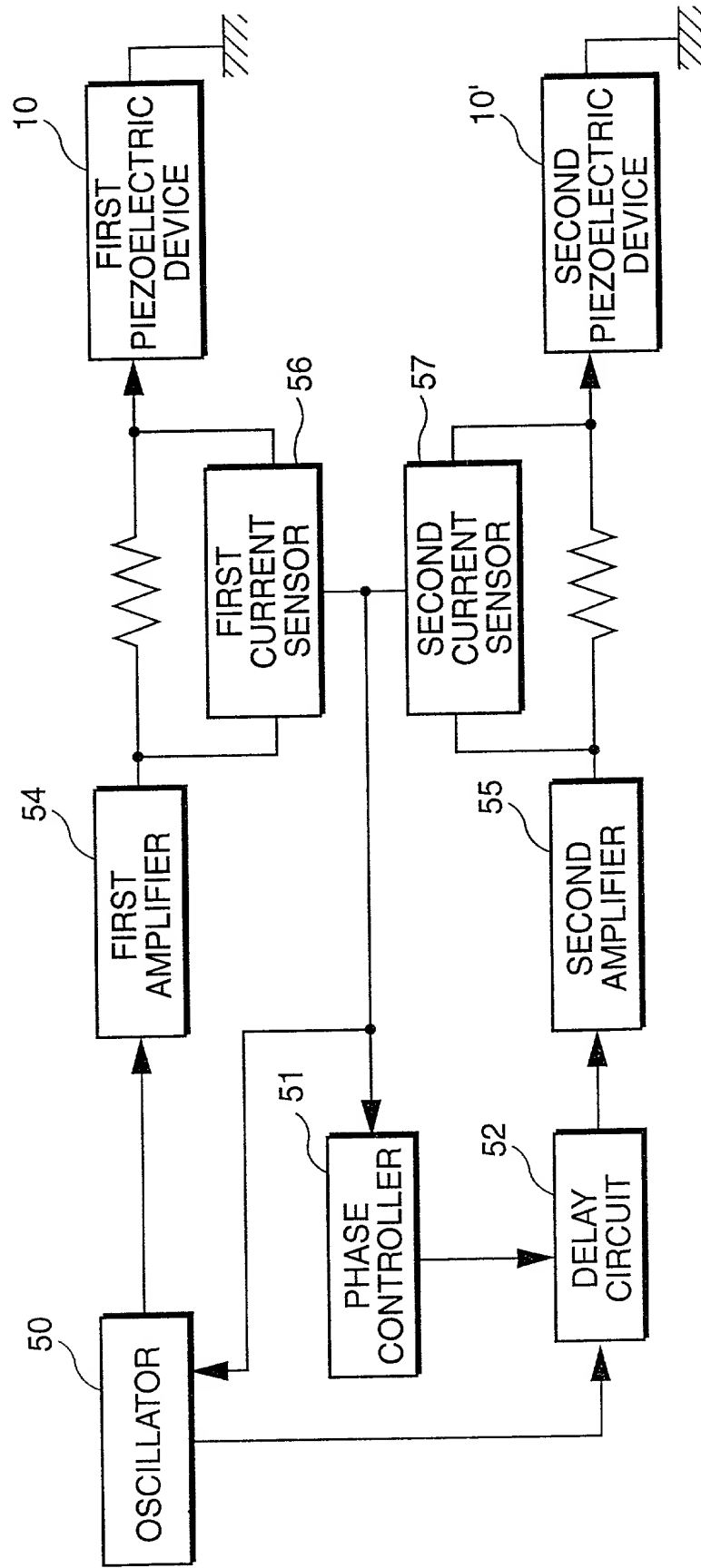


FIG. 23



[illegible]

My residence, post office address and citizenship are as stated below next to my name,

ACTUATOR AND DRIVING METHOD THEREOF

(check one) XX is attached hereto.

as Application Serial No. _____

(if applicable)

I hereby claim foreign priority benefits under 35 U.S.C. 119(a)-(d) or 365(b) of any foreign application(s) for patent or inventor's certificate, or 365(a) of any PCT international application which designated at least one country other than the United States of America, listed below and have also identified below, by checking below, any foreign application for patent or inventor's certificate, or of any PCT international application having a filing date before that of the application on which priority is claimed.

			Priority Claimed	
<u>11-166919(PAT.)</u>	<u>Japan</u>	<u>14/June/1999</u>	<u>X</u>	<u> </u>
(Number)	(Country)	(Day/Month/Year Filed)	Yes	No
<u>11-185197(PAT.)</u>	<u>Japan</u>	<u>30/June/1999</u>	<u>X</u>	<u> </u>
(Number)	(Country)	(Day/Month/Year Filed)	Yes	No

I hereby claim the benefit under 35 U.S.C. 119(e) of any United States provisional application(s) listed below.

(Application Number)

(Filing Date)

I hereby claim the benefit under 35 U.S.C. 120 of any United States application(s), or 365(c) of any PCT international application designating the United States of America, listed below and, insofar as the subject matter of each of the claims of this application is not disclosed in the prior United States or PCT International application in the manner provided by the first paragraph of 35 U.S.C. 112, I acknowledge the duty to disclose information which is material to patentability as defined in 37 CFR 1.56 which became available between the filing date of the prior application and the national or PCT international filing date of this application.

(Appl. Serial No.)

(Filing Date)

(Status) (patented,
pending, abandoned)

POWER OF ATTORNEY: As a named inventor, I hereby appoint the following attorney(s) and/or agent(s) to prosecute this application and transact all business in the Patent and Trademark Office connected therewith. (list name and registration number)

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I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

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